

# **SPIRAL and RF-PASS Three Dimensional Design and Analysis Tools for RF Integrated Circuits**

**By  
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## Acknowledgements

Jerry Tallinger – OEA International, Inc.

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## Agenda

- **Introduction to On-chip RF Components**
- **On-chip Inductors**
- **Why can not we use Pre-characterized Inductors**
- **Inductance Concepts**
- **Test Chip Results**
- **A Real Spiral Inductor Design**
- **Simplified “curve-fit” Model Generation**
- **On-chip Capacitor Designs**
- **Conclusions**



# FABLESS SEMICONDUCTOR ASSOCIATION

## OEA RF/Analog Software Products

### ***SPIRAL™***

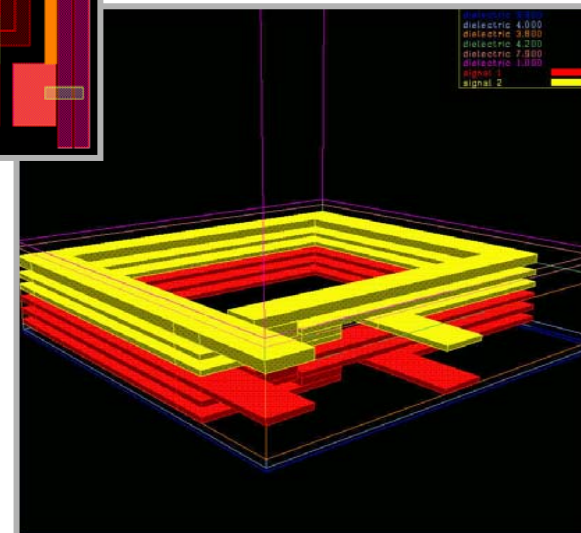
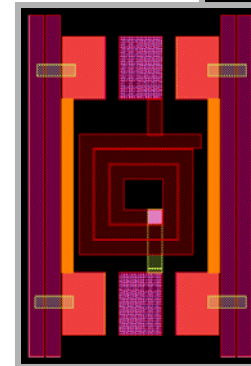
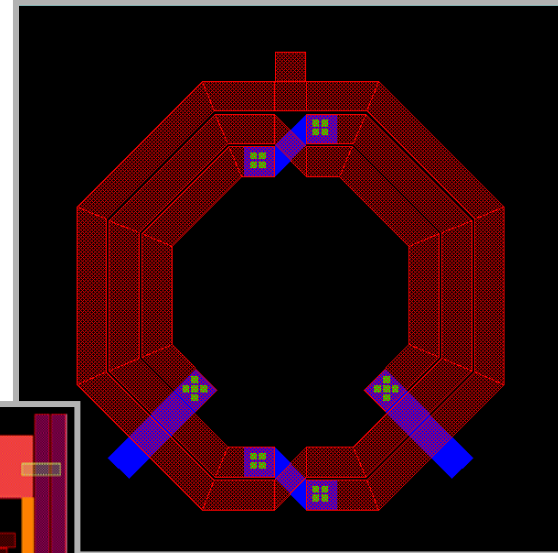
- Includes all relevant effects (skin, substrate, etc...)
- Synthesizes a large variety of inductors
- Can examine thousands of designs in a few hours
- Generates layout, Spice, Z & S parameters
- Can fit to many simplified models
- Optimization engine included

### ***RF-PASS™***

- Outputs N-Port Y, Z and S parameters
- Handles much more complex substrates and designs
- Optimization of arbitrarily complex passive structures

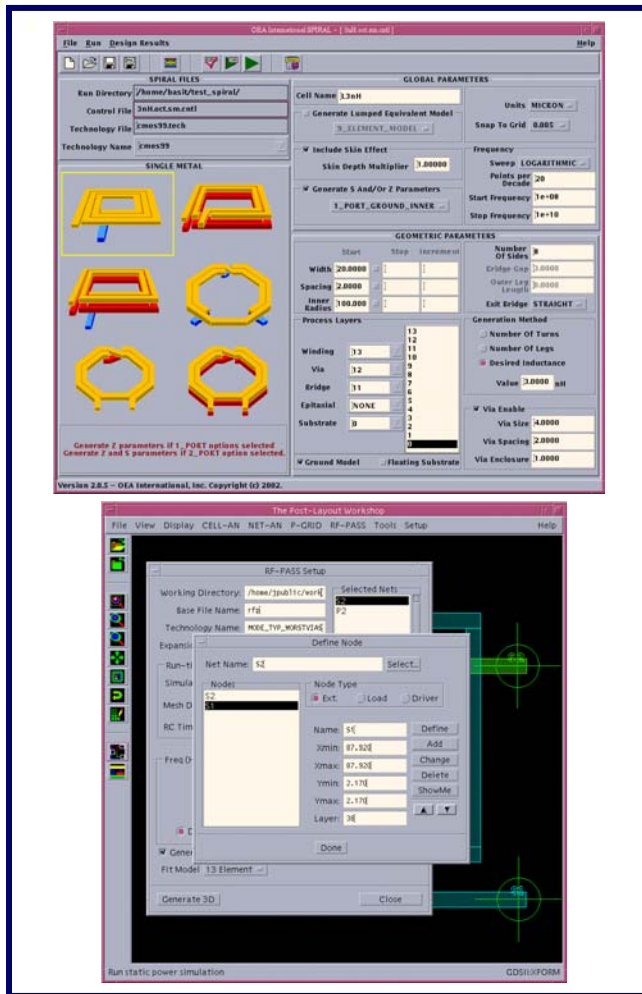
### ***SUBSTRATE NOISE ANALYSIS***

- Calculates full-chip substrate noise couplings
- Enables what-if exploration of isolation strategies
- Allows design planning before layout

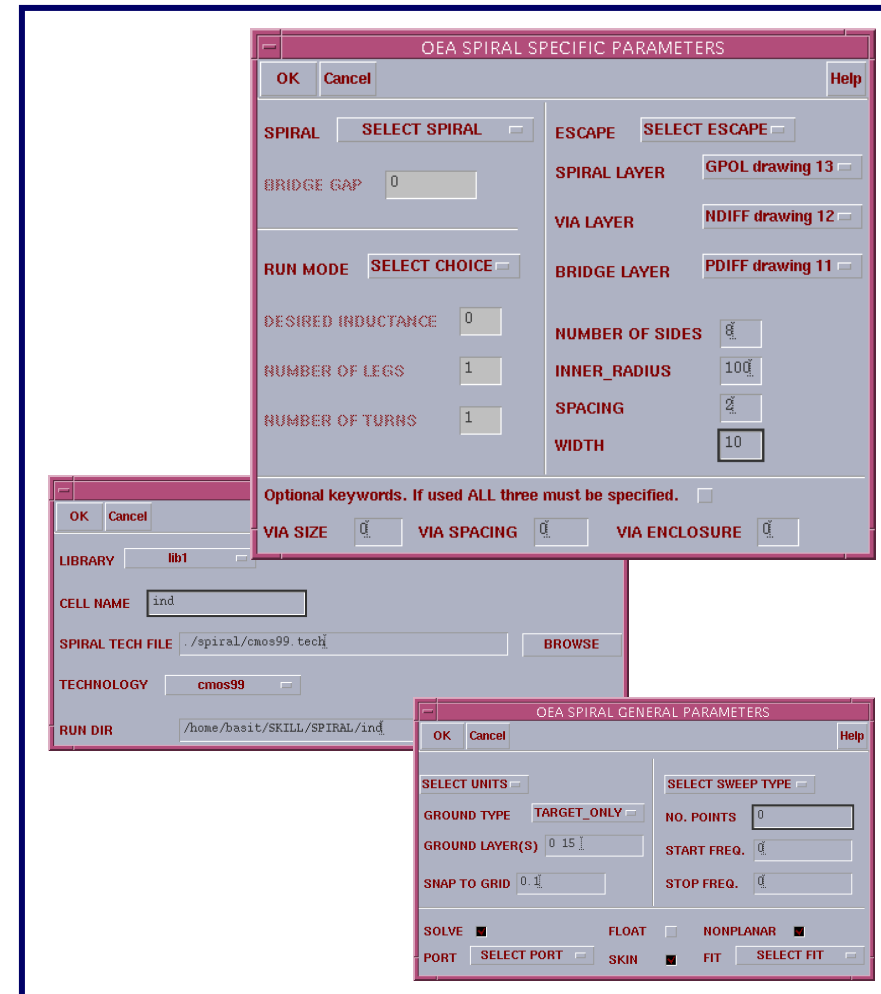


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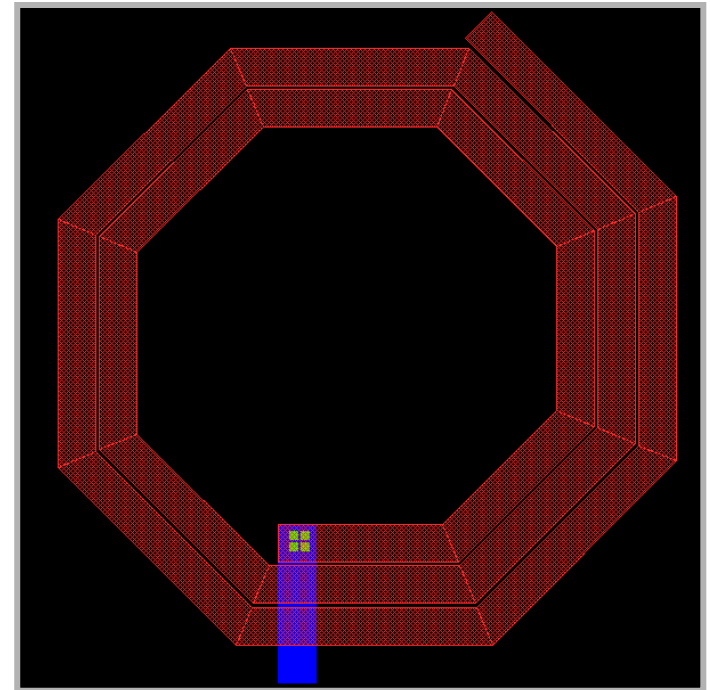
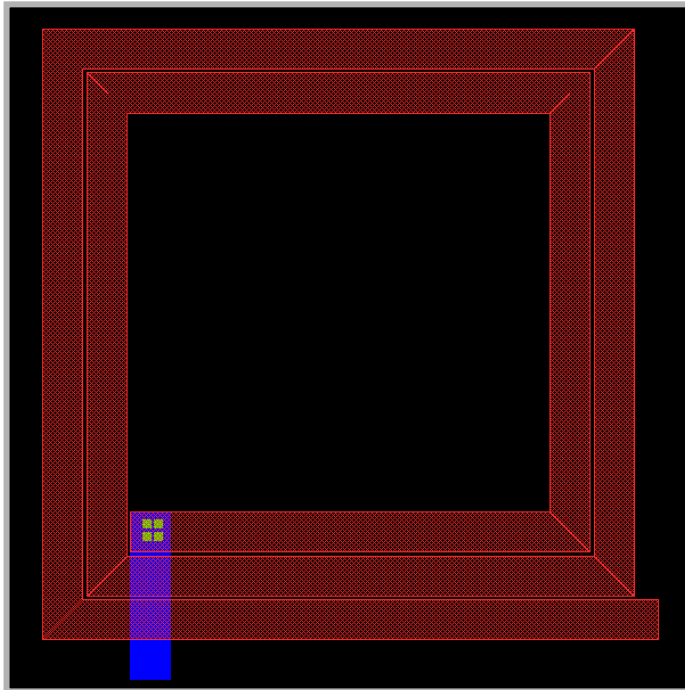
Generic UNIX Interfaces



Cadence Interface

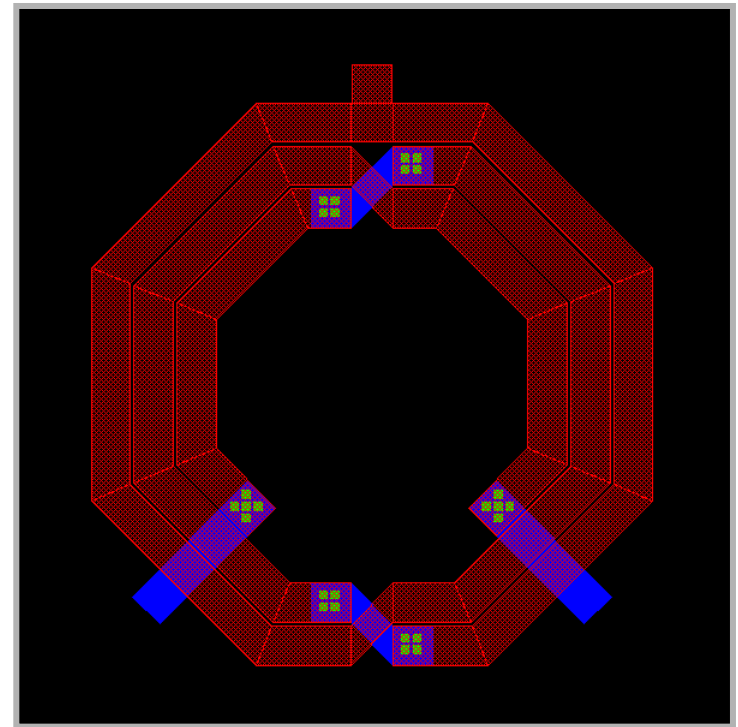
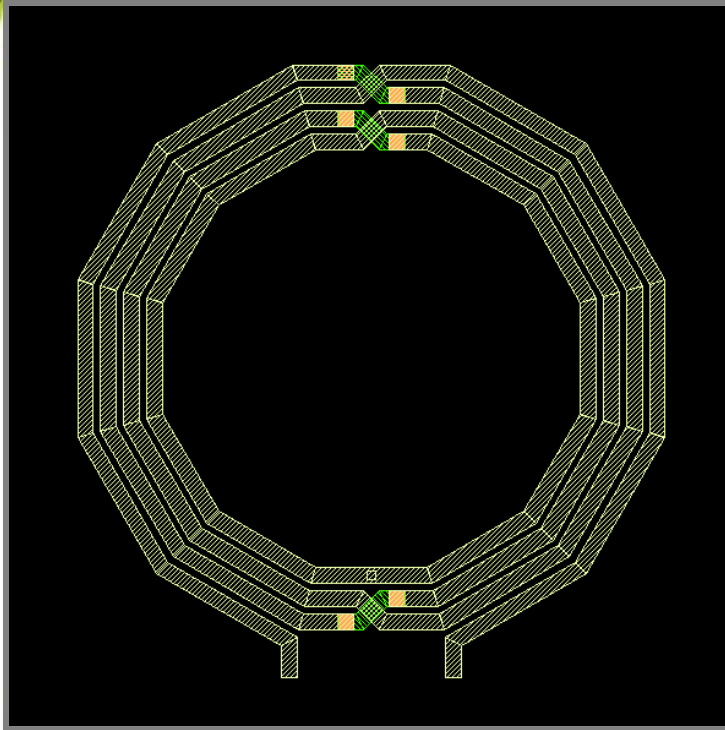


## Standard Inductors: 4 sided / 8 sided



- Usually uses top metal layer for winding
- Can use multiple metal layers in parallel
  - Lowers series resistance
  - Increases capacitance
- Can use multiple metal layers in series (coil)

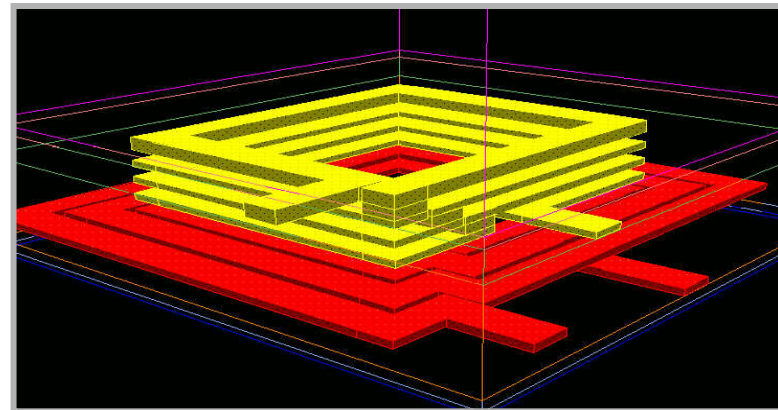
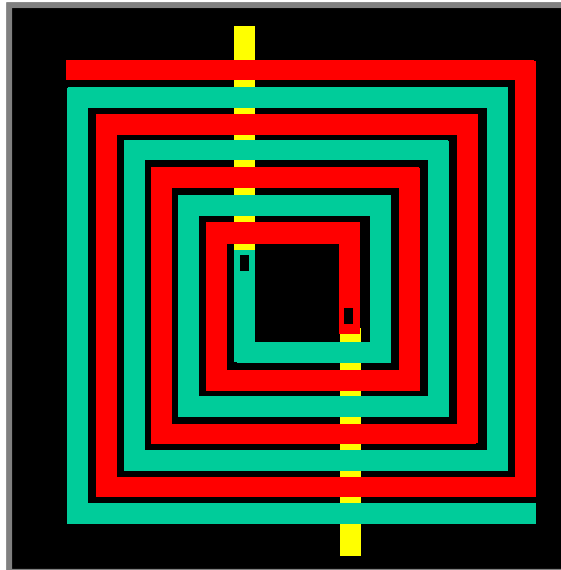
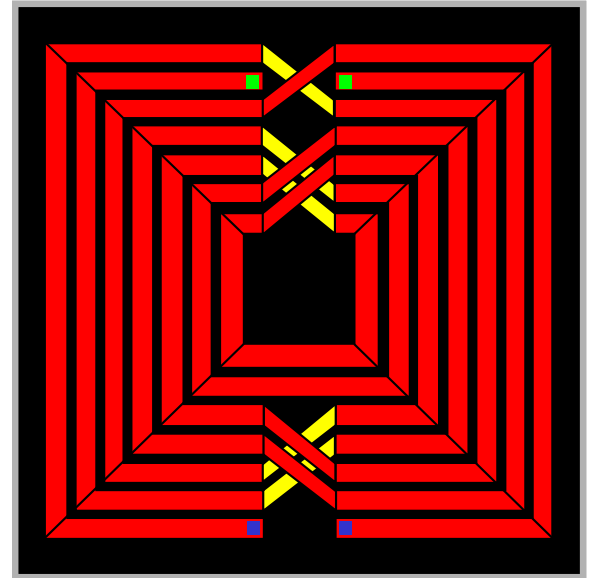
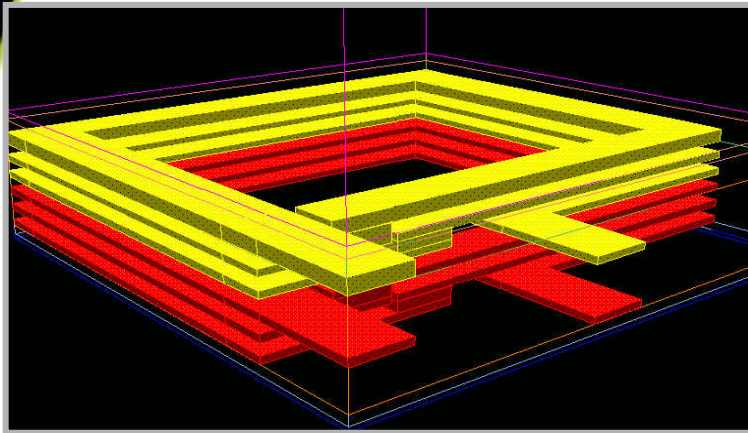
## Symmetric Differential Inductors



- **Symmetric Center Tapped Inductors instead of 2 'uncoupled' inductors:**
  - Easily defined center tap
  - Reduced chip area
  - Higher Q (reduced substrate losses)
  - No need to model parasitic coupling



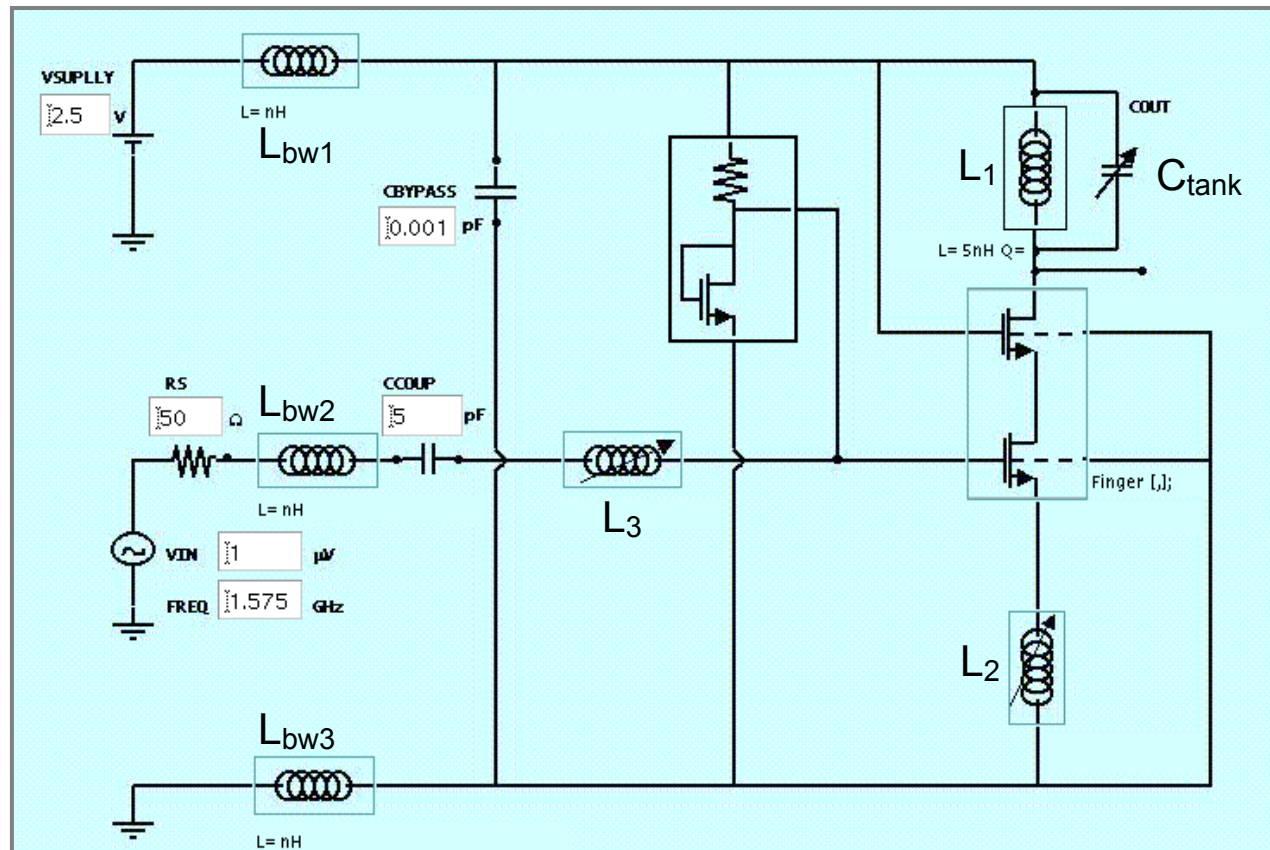
## Transformers and Baluns





# FABLESS SEMICONDUCTOR ASSOCIATION

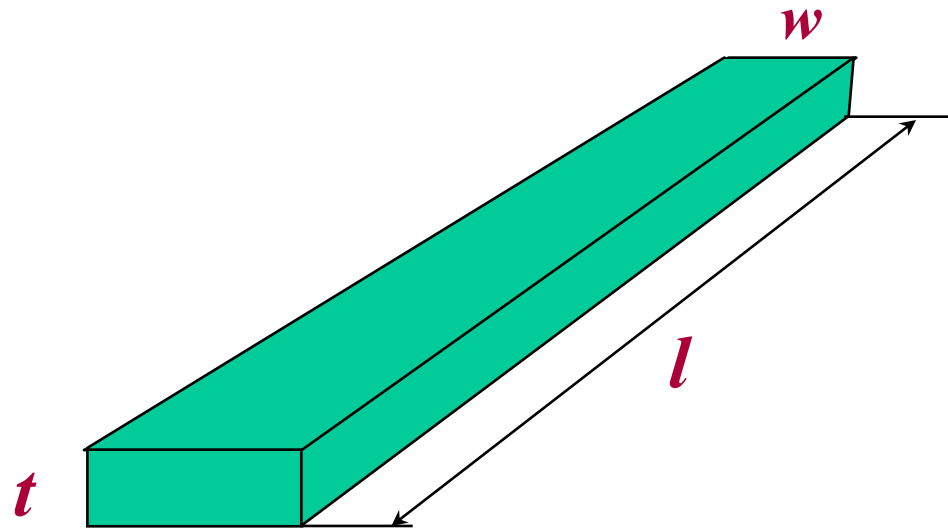
**CMOS LNA Example to Show one can not use Pre-characterized Inductors for an Optimal Design !**



**L<sub>1</sub>, L<sub>2</sub>, L<sub>3</sub>, C<sub>tank</sub> and Transistor Sizes are all related!**



## Inductance of a Rectangular Conductor



$$L(\mu\text{H}) = 0.002l \left\{ \ln \left[ \frac{2l}{(w+t)} \right] + 0.5 - k \right\}$$

$$R(\Omega) = \frac{\delta l}{(w t)}$$

Where  $k = f(w, t)$

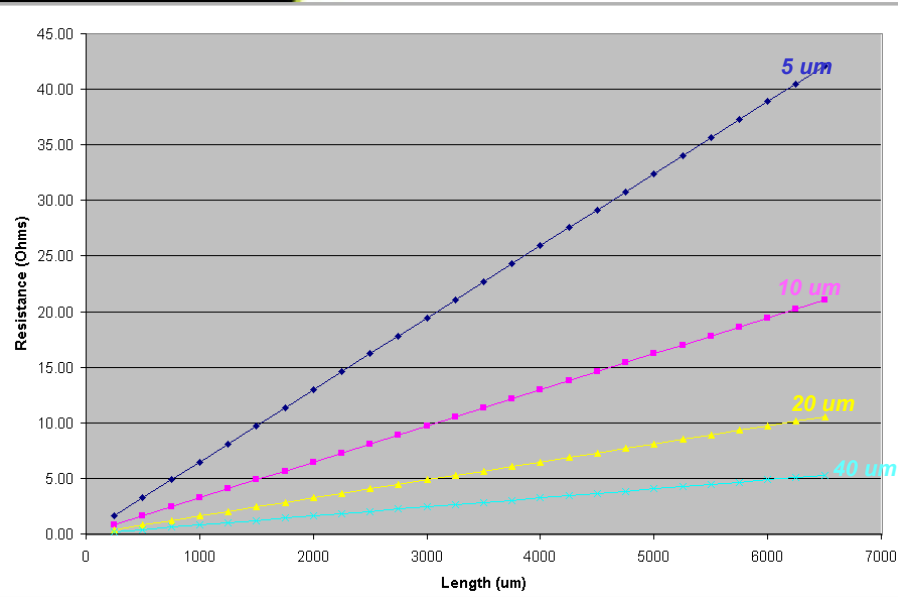
$0 < k < 0.0025$

$l, t, w$  in cm

$$Z(j\omega) = R + j\omega L \quad \text{Where } \omega = 2\pi f$$



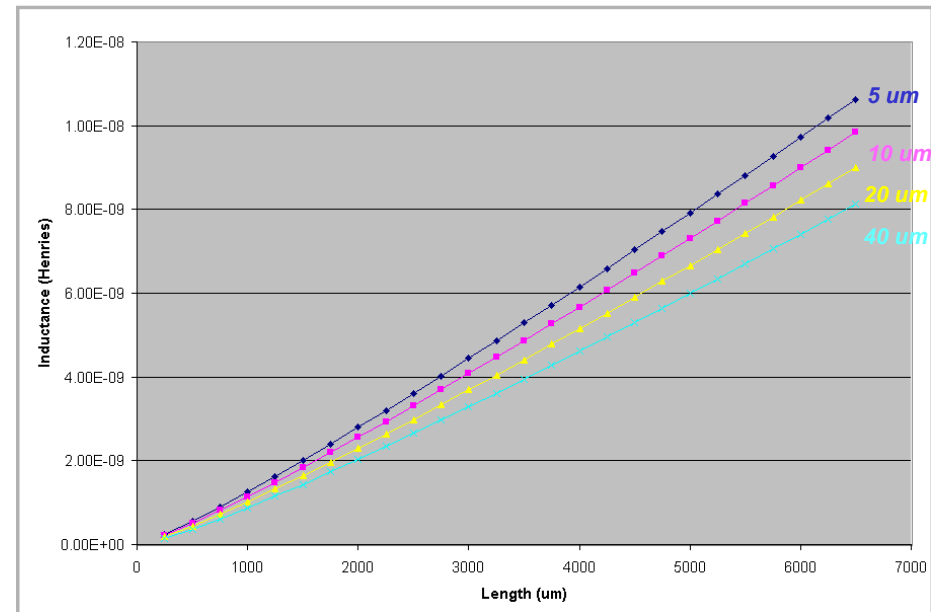
# FABLESS SEMICONDUCTOR ASSOCIATION



**DC Resistance vs. Length at Various Widths (1 μm Thick Aluminum)**



**Inductance vs. Length at Various Widths**



## Q and $f_{pass}$ of a Rectangular Conductors

$$Q = \frac{\text{Im}[Z(j\omega)]}{\text{Re}[Z(j\omega)]} = \frac{L\omega}{R} = \frac{L2\pi f}{R}$$

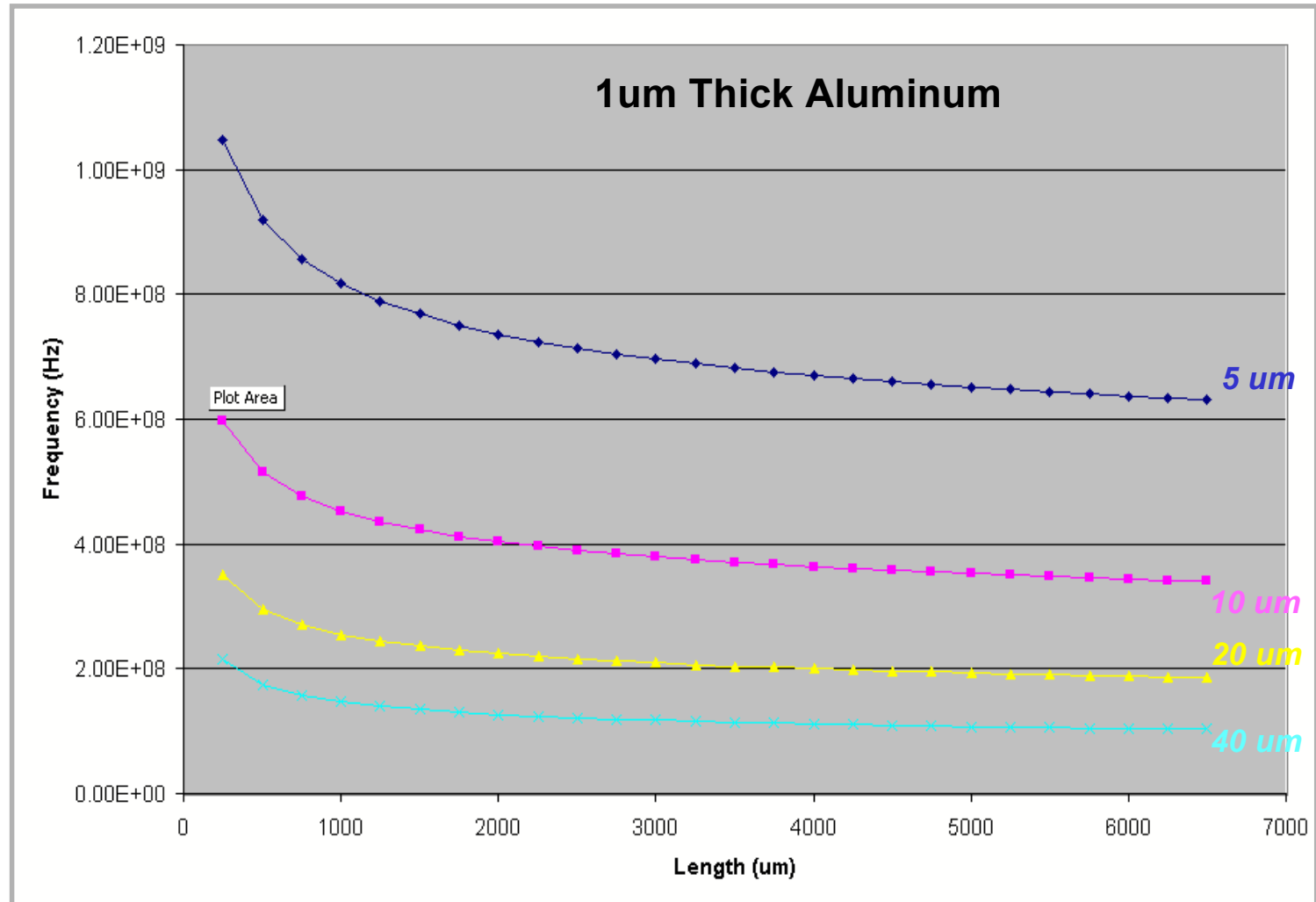
$$Q = \frac{0.002wt \left[ \ln \left( \frac{2l}{w+t} \right) + 0.5 - k \right] \omega}{\delta}$$

$$Q = 1 \Rightarrow f = \frac{R}{2\pi L}$$

$$f_{pass} = \frac{R}{2\pi L} = \frac{\delta}{0.002wt \left[ \ln \left( \frac{2l}{w+t} \right) + 0.5 - k \right] 2\pi}$$



## Minimum Frequencies for Onset of Inductive Behavior





## Partial Inductance Approach

Six Self Inductances:  $L_1, L_2, L_3, L_4, L_5, L_6$

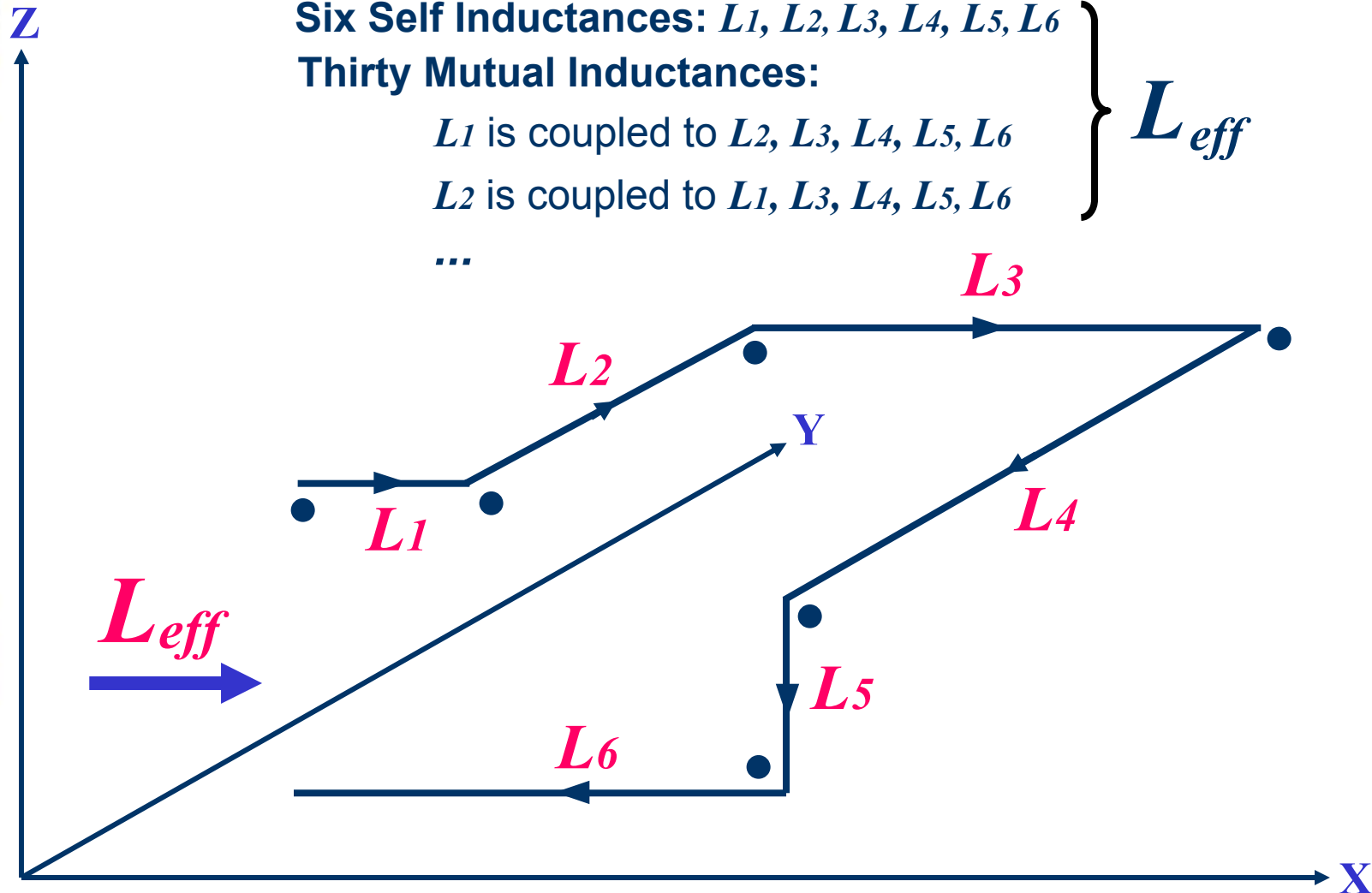
Thirty Mutual Inductances:

$L_1$  is coupled to  $L_2, L_3, L_4, L_5, L_6$

$L_2$  is coupled to  $L_1, L_3, L_4, L_5, L_6$

...

$L_{eff}$



## Inductance Matrix Representation

$$\begin{bmatrix}
 \textcolor{red}{L11} & L12 & \dots & L16 \\
 L21 & \textcolor{red}{L22} & \dots & L26 \\
 \vdots & & & \\
 L61 & L62 & \dots & \textcolor{red}{L66}
 \end{bmatrix}$$

$L_{eff} = \sum_{i=1}^n \sum_{j=1}^n L_{i,j}$   
 $L_{i,j} = L_{j,i}$

→ Self Inductance Diagonals > 0

Off Diagonals  
Mutual Inductance

Can have < 0, > 0, or 0 value in Henry



## Neumann Formulation of Mutual Inductance

Diagram illustrating the Neumann Formulation of Mutual Inductance. The diagram shows two wire segments,  $AB$  and  $CD$ , in a 3D coordinate system with axes  $X$ ,  $Y$ , and  $Z$ .

- Segment  $AB$  is defined by points  $A$  (labeled  $s_1$ ) and  $B$  (labeled  $s_2$ ). A unit vector  $\vec{u}$  is shown along  $AB$ . A point on this segment is labeled with coordinates  $x, y, z$ .
- Segment  $CD$  is defined by points  $C$  (labeled  $s'_1$ ) and  $D$  (labeled  $s'_2$ ). A unit vector  $\vec{v}$  is shown along  $CD$ . A point on this segment is labeled with coordinates  $x', y', z'$ .
- A vector  $\vec{r}$  connects the point  $(x, y, z)$  on segment  $AB$  to the point  $(x', y', z')$  on segment  $CD$ .

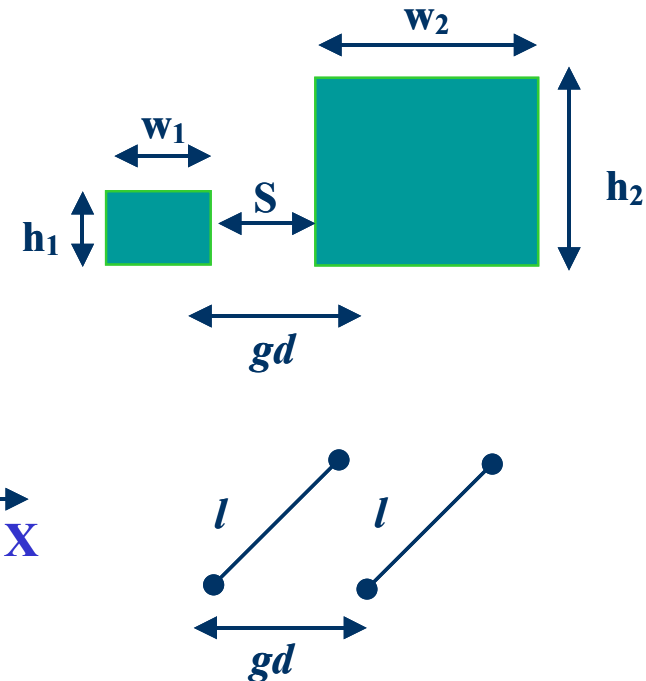
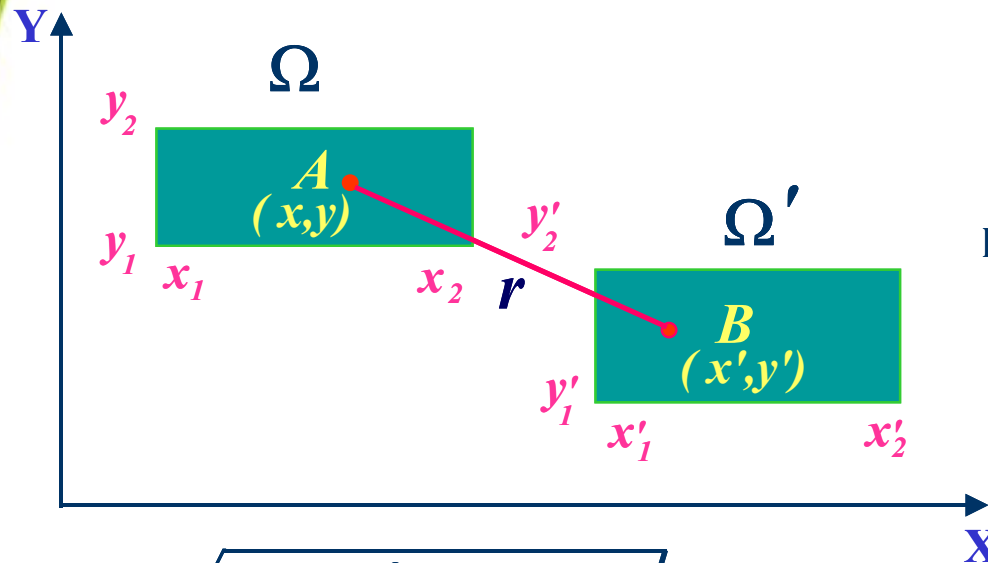
$$L_{i,j} = \int_{s'_1}^{s'_2} \int_{s_1}^{s_2} \frac{\vec{u} \cdot \vec{v}}{r} ds ds'$$

$\vec{u} \rightarrow$  unit vector along  $AB$   
 $\vec{v} \rightarrow$  unit vector along  $CD$

$$r = \sqrt{(x - x')^2 + (y - y')^2 + (z - z')^2}$$



## Geometric Distance Between Objects



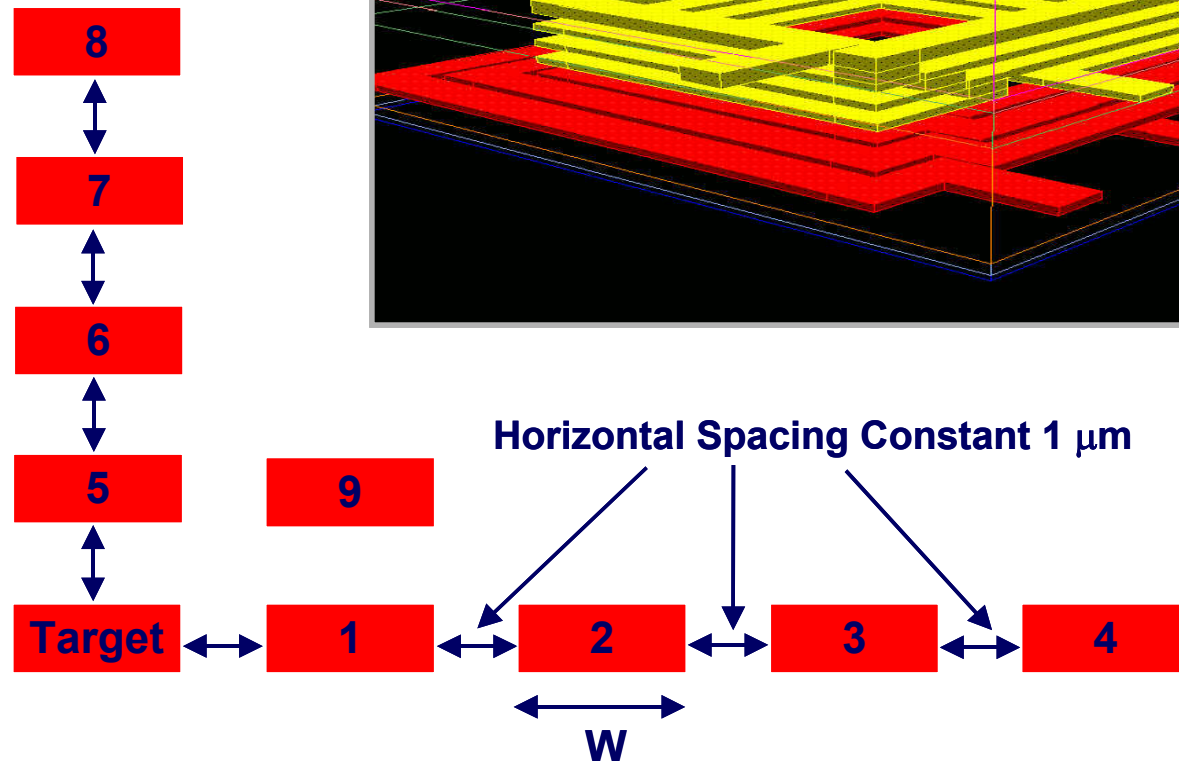
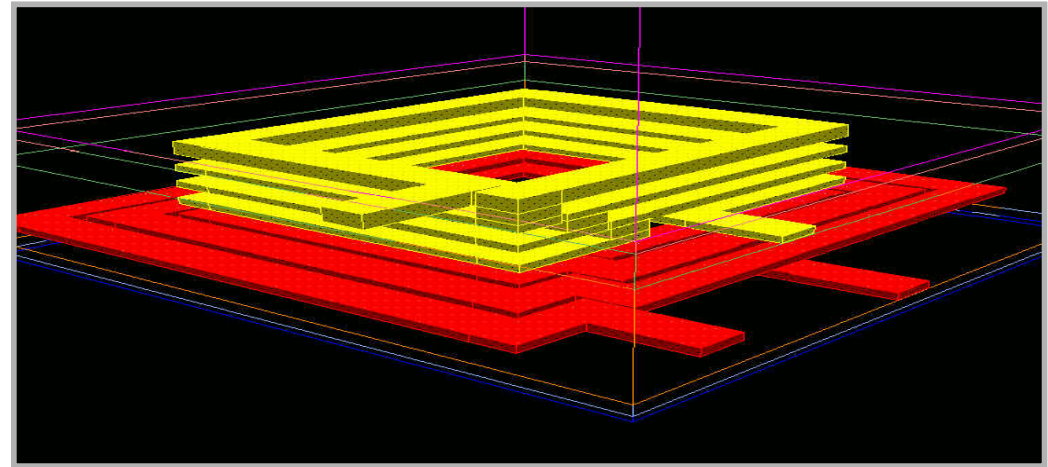
$$r = \sqrt{(x - x')^2 + (y - y')^2}$$

$$gd = \int_{\Omega'} \int_{\Omega} \ln(r) d\Omega d\Omega'$$

$$gd = \int_{y'=y_1'}^{y_2'} \int_{y=y_1}^{y_2} \int_{x'=x_1'}^{x_2'} \int_{x=x_1}^{x_2} \ln \sqrt{(x - x')^2 + (y - y')^2} dx dx' dy dy'$$



### Vertical Spacing Constant $1\text{ }\mu\text{m}$

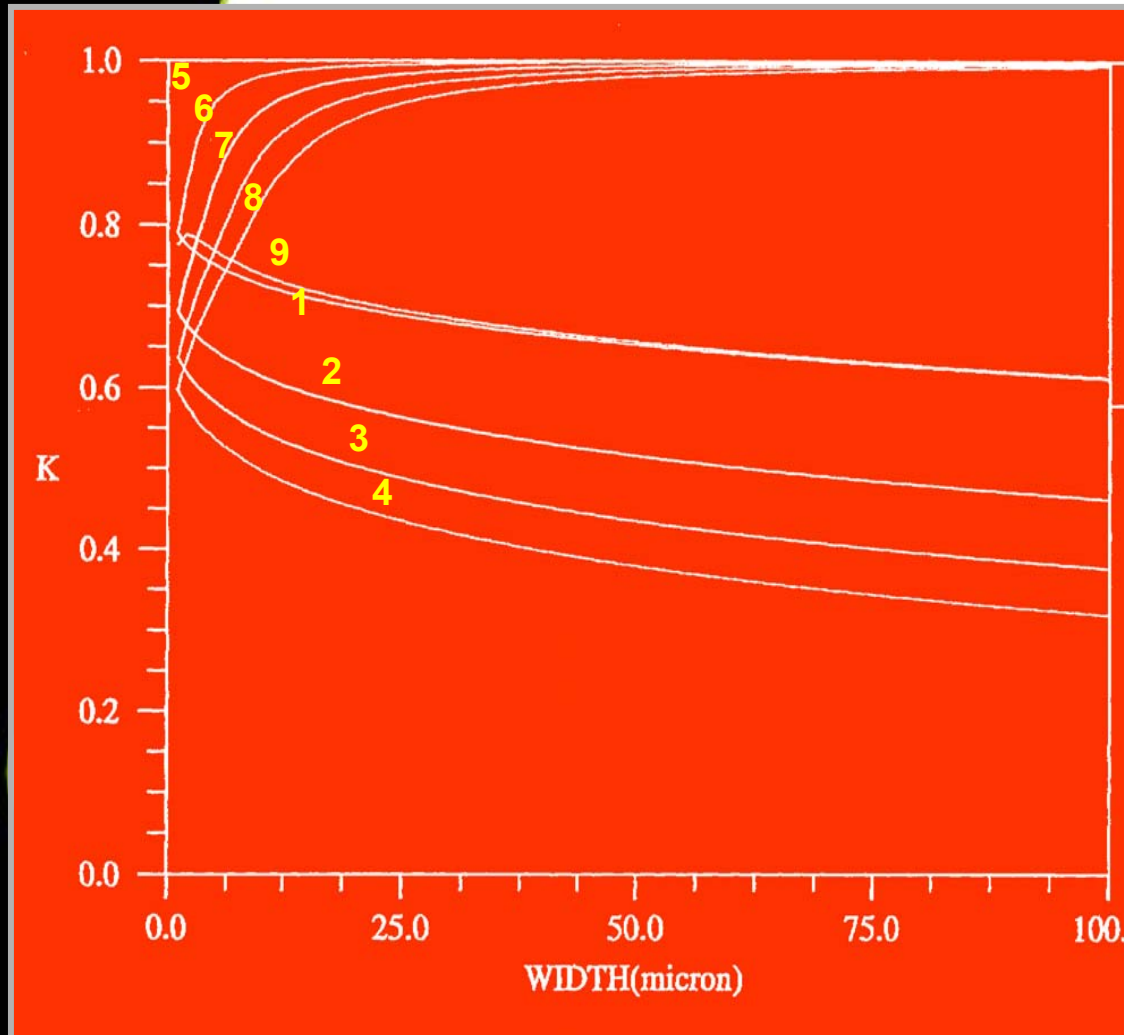


## Target and Nine Conductors are all the Same Width



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## Mutual Inductive Coupling as a Function of Width



$$K_{nm} = \frac{L_{nm}}{\sqrt{L_{nn} L_{mm}}}$$

8

7

6

5

9

Target

1

2

3

4

## **Detractors from Q**

**Capacitive effects**

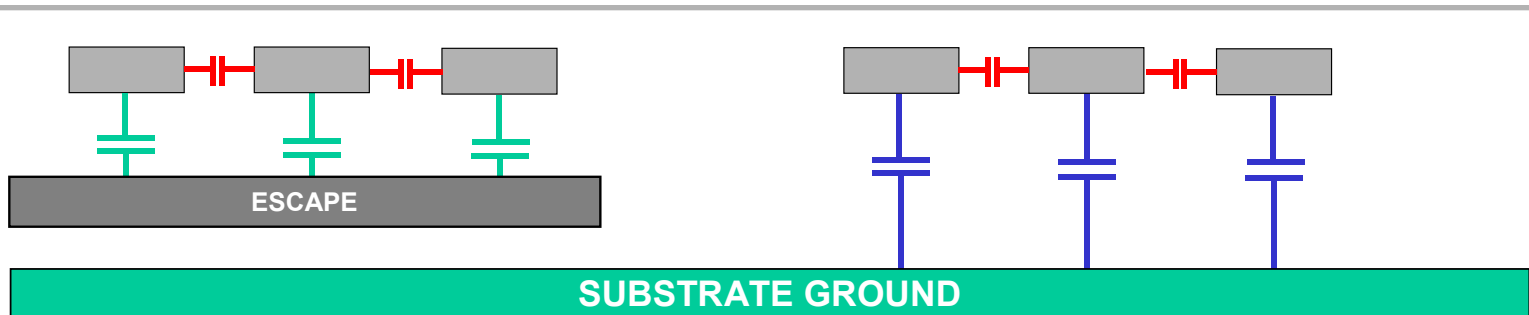
**Skin and Proximity effect in Conductors**

**Eddy and Displacement Currents in  
Substrate**

**Radiative Losses**



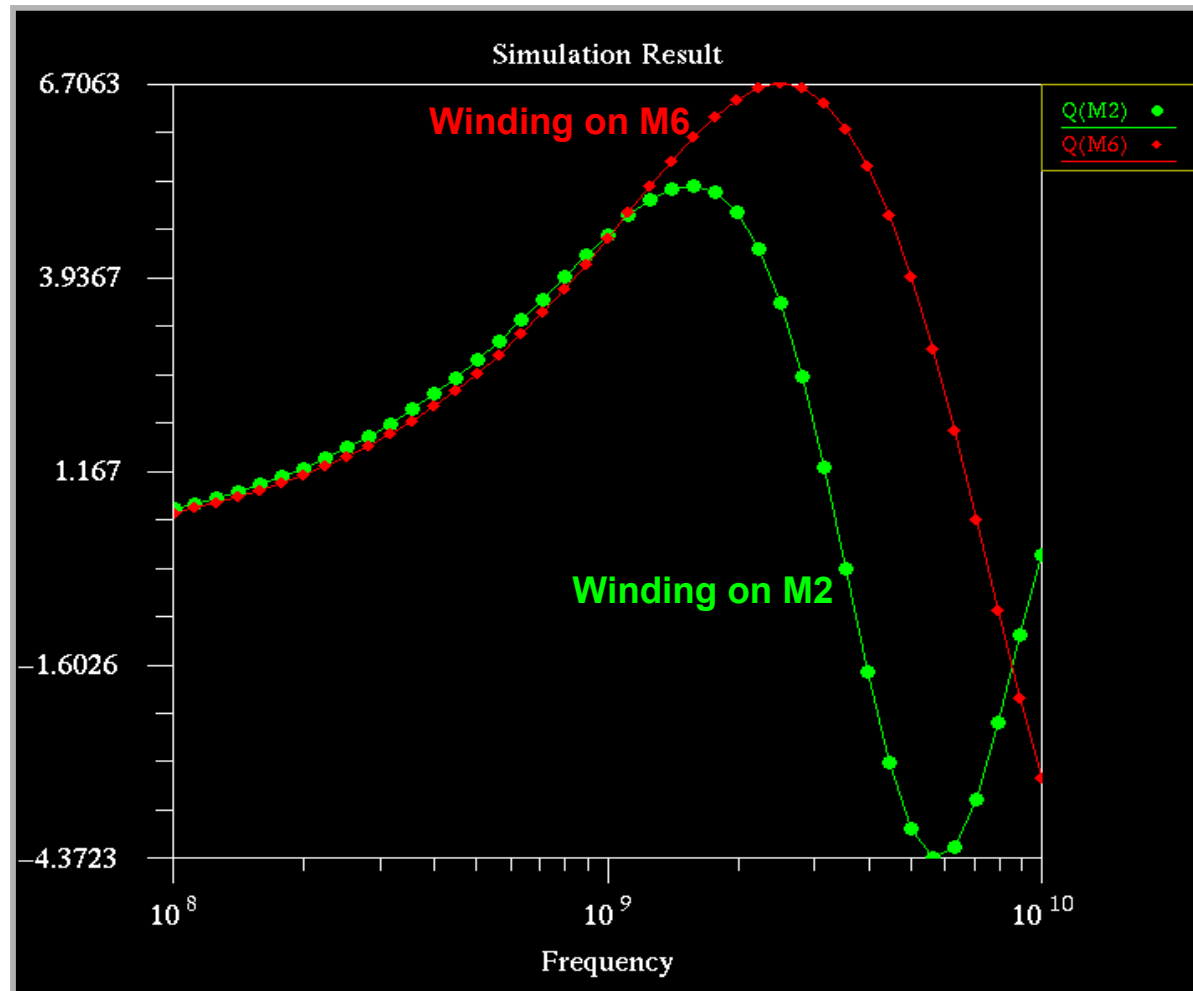
## Simple Capacitance Model of an Inductor



- **Capacitance to Ground**
  - Increases with width
  - Increases with spacing
  - Use highest metal level
- **Capacitance between windings**
  - Less important for Si substrate
- **Capacitance between winding and escape**
- **Capacitance within substrate**



## Q vs. Frequency for Two Inductors (All metal layers have same thickness and $\rho$ )



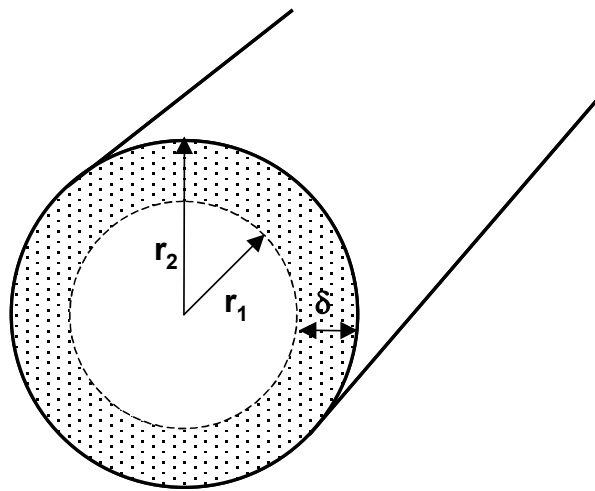
## Skin Depth Area of a Conductor

$$A_1 = \pi r_1^2$$

$$A_2 = \pi r_2^2$$

$$\text{Skin Depth Area} = A_2 - A_1 = \pi(r_2^2 - r_1^2)$$

$$\delta = r_2 - r_1$$



RF current flow in shaded region

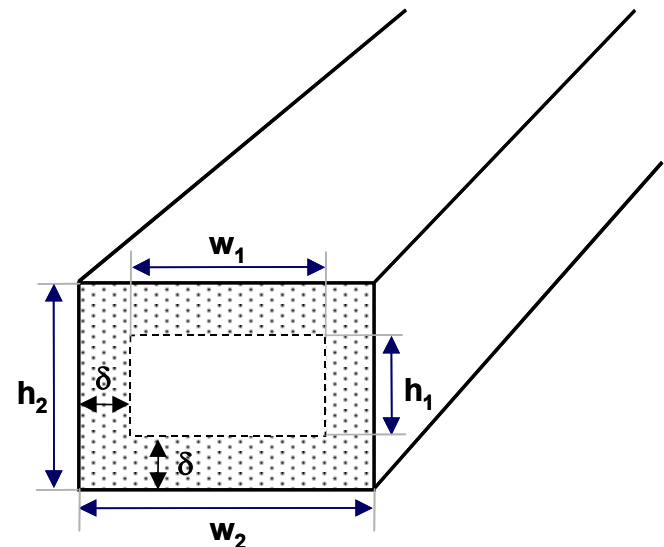
$$A_1 = w_1 h_1$$

$$A_2 = w_2 h_2$$

$$\text{Skin Depth Area} = A_2 - A_1 = w_2 h_2 - w_1 h_1$$

$$\delta = \sqrt{\frac{2}{\omega \mu \sigma}}$$

$$2\delta = w_2 - w_1 = r_2 - r_1$$

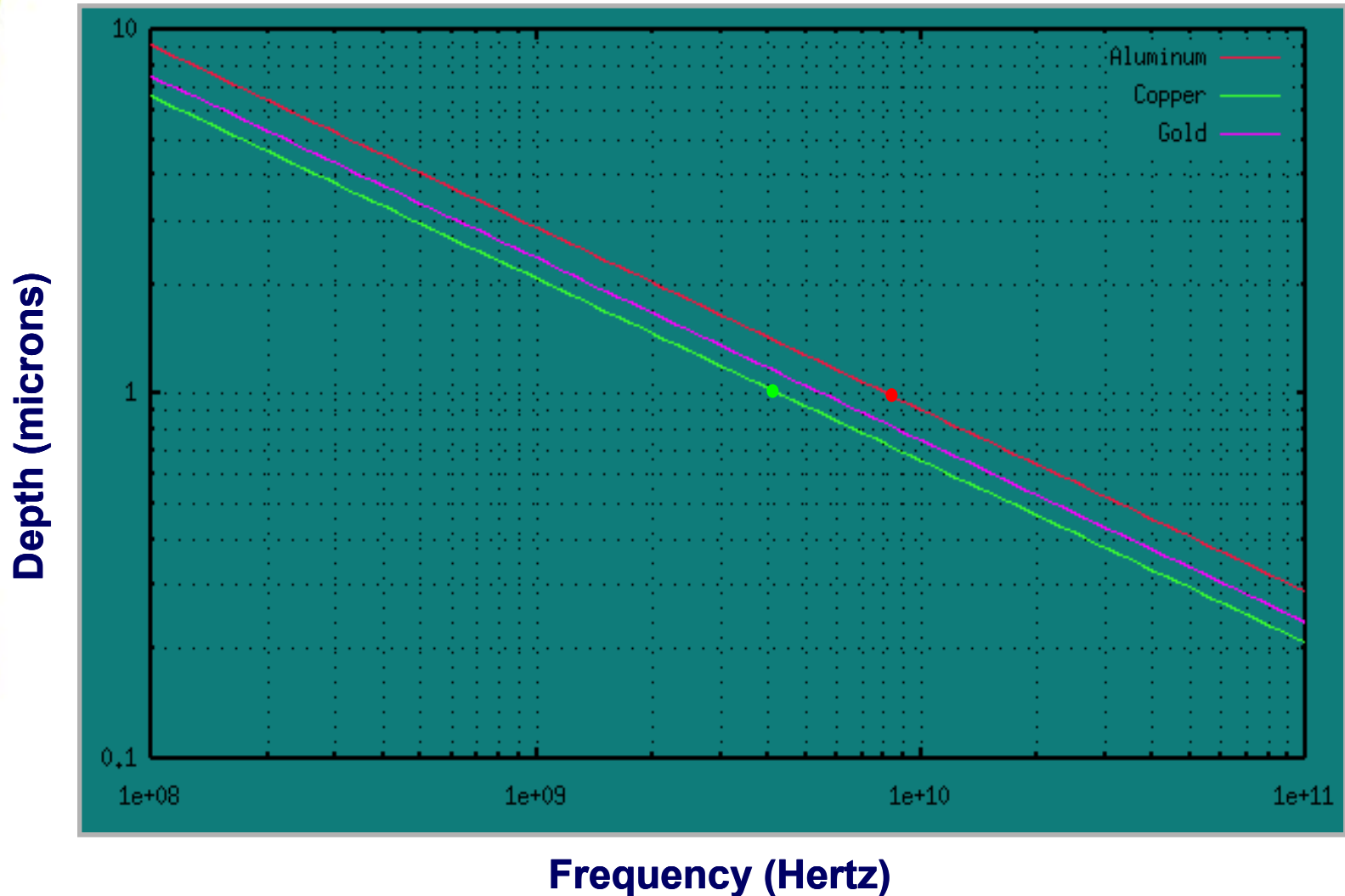


RF current flow in shaded region





## Skin Depth of Commonly Used Metals



## Skin Effect in Conductors

Example shows currents in opposing directions.



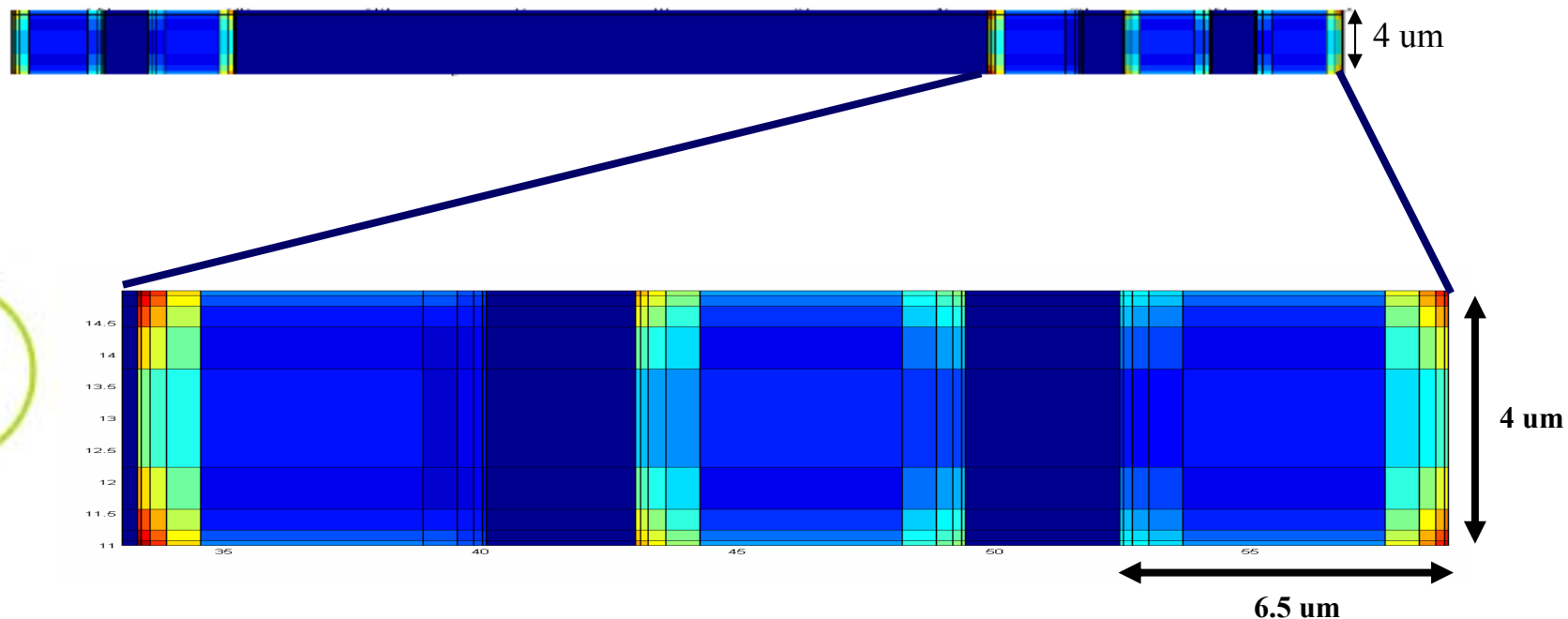
Low frequency currents are distributed across the entire cross sectional area to take path of minimum resistance.

High frequency currents are distributed to minimize mutual inductance thus minimizing impedance.

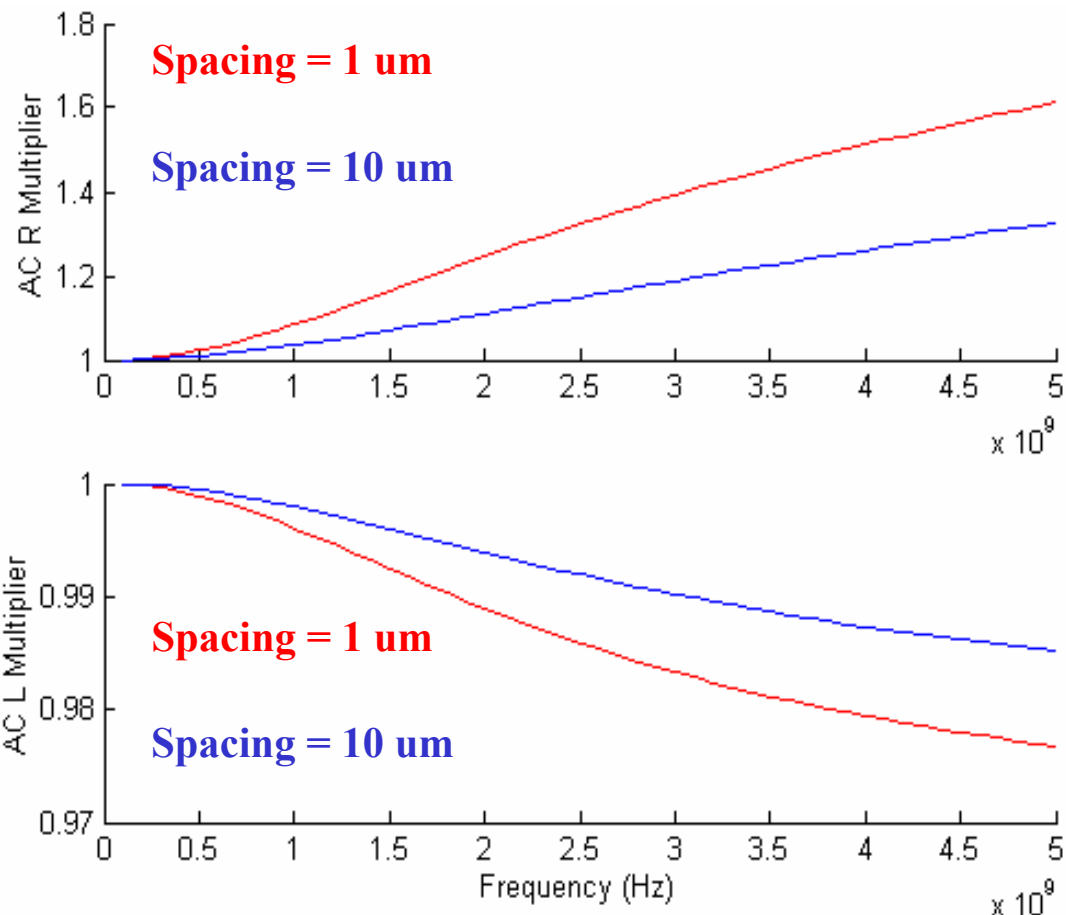


## Current Distribution Due to Skin and Proximity Effects

2.5 Turn Square Spiral  
100  $\mu\text{m}$  Inner Diameter  
6.5  $\mu\text{m}$  Width  
4  $\mu\text{m}$  Thickness  
2.1  $\mu\text{m}$  Spacing



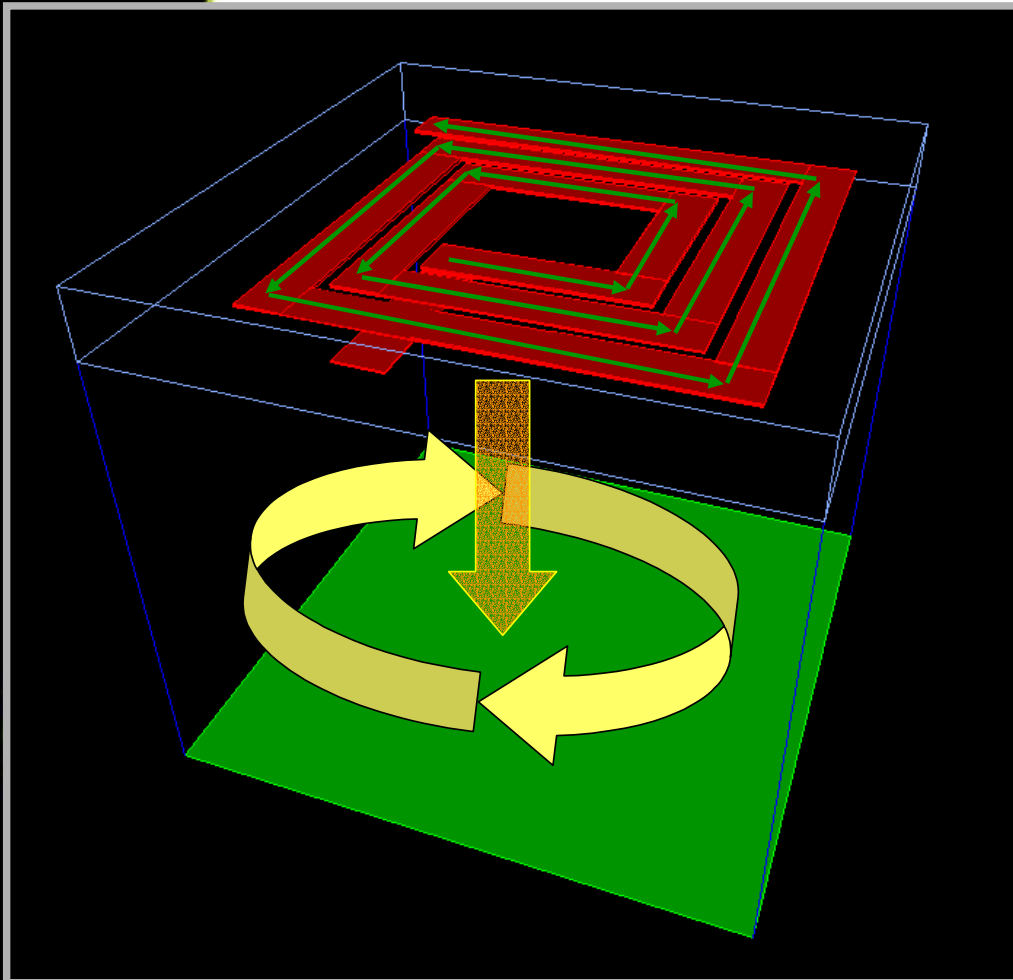
## AC Resistance & Inductance Comparison For 1 $\mu$ m and 10 $\mu$ m Spacing



Five Turns, Outer spiral diameter = 200  $\mu$ m, Width = 10  $\mu$ m



## Reducing Substrate Losses (Some Partially Useful Methods)



- Use high resistivity substrate
- Patterned shields
  - Limited Use
  - Significant Noise coupling
  - Reduced operating frequency
- Depletion region
- Keep inductor small



## Radiative Losses

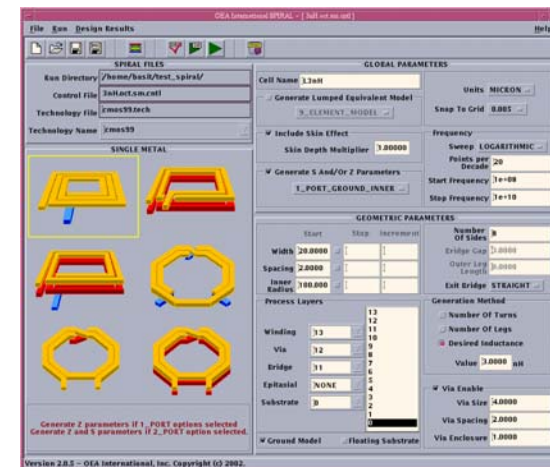
- On chip inductors make very poor antennas
  - No need to worry about radiation loss in most cases
  - However, should be careful near quarter wavelength

$V_p$  = Propagation Velocity = Phase Velocity

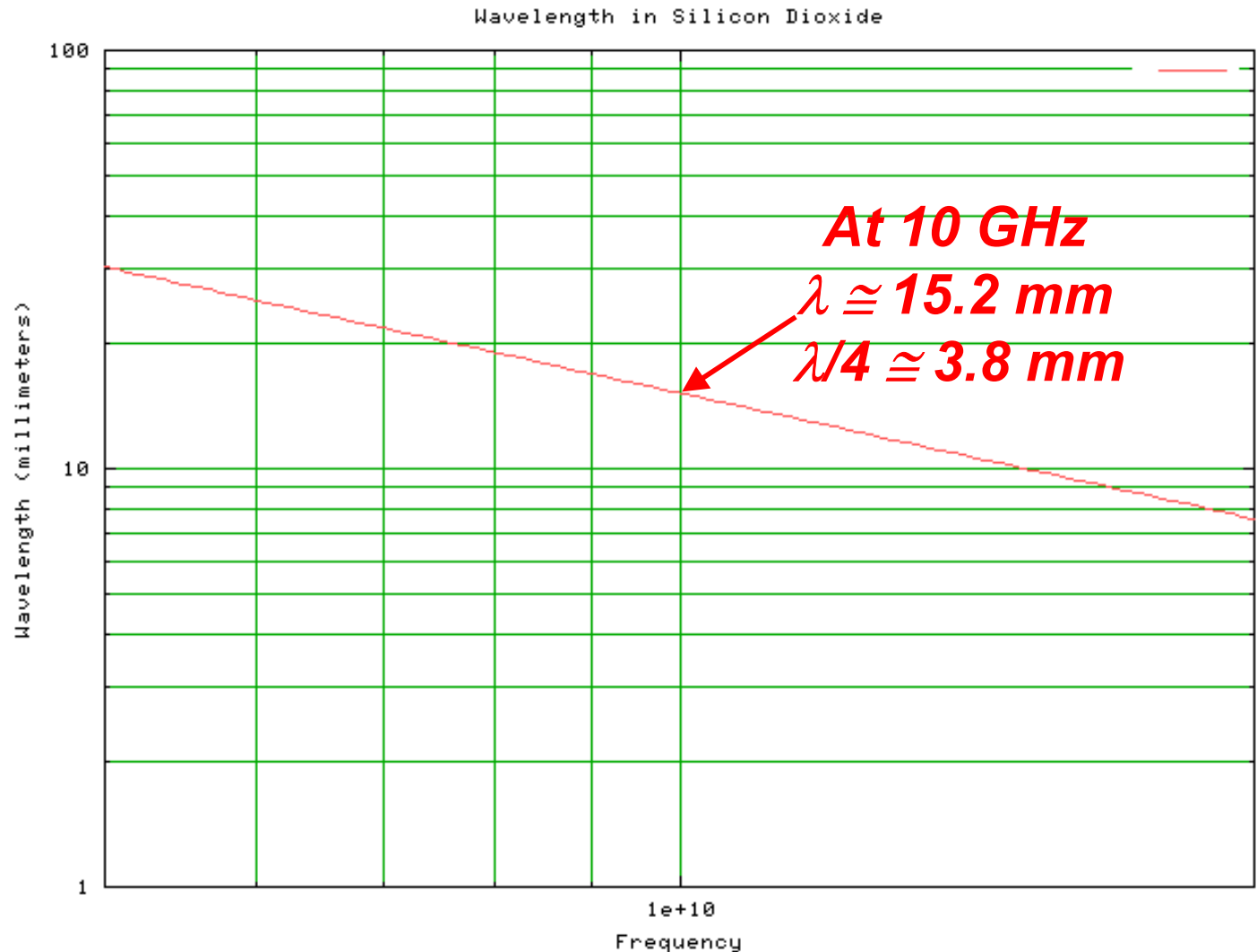
$$V_p = 1/\sqrt{\mu\epsilon} = 1/\sqrt{LC}$$

$$V_p = f\lambda$$

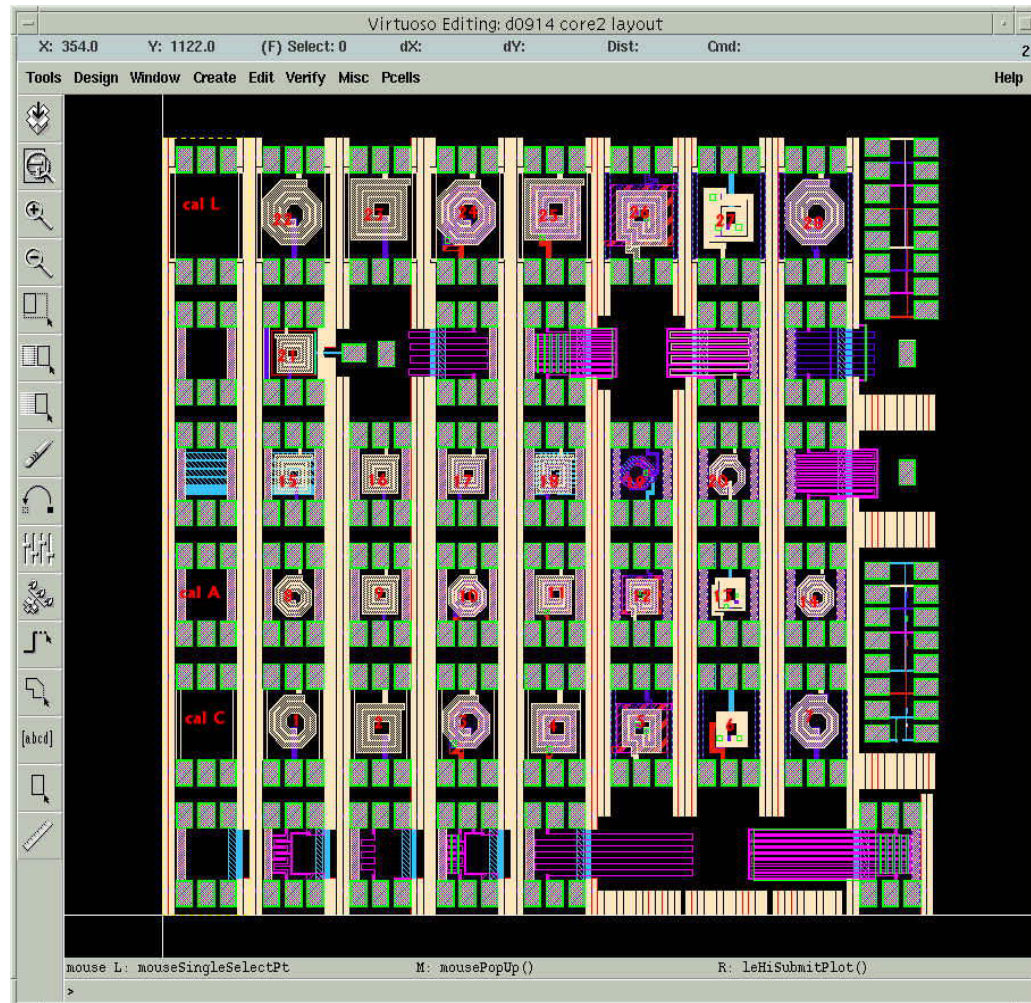
$$\lambda = (1/\sqrt{\mu\epsilon}) / f$$



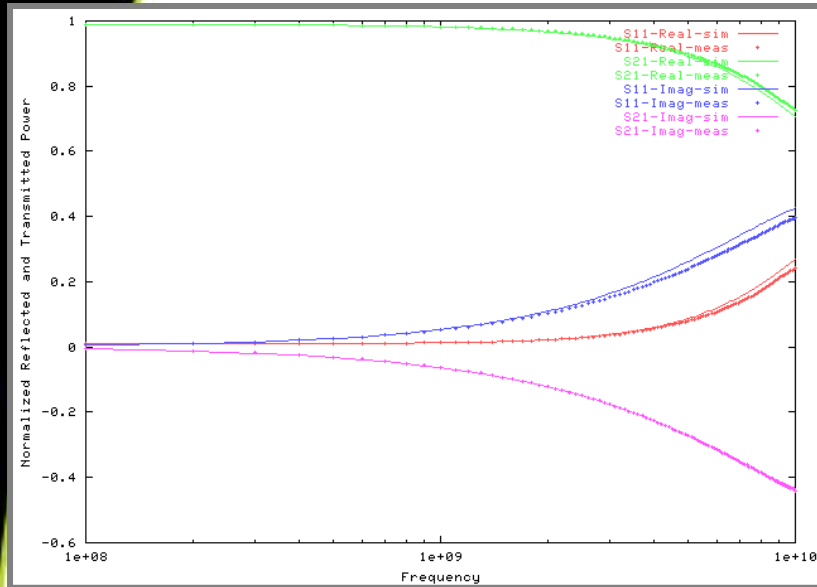
## Wavelength vs. Frequency in $\text{SiO}_2$



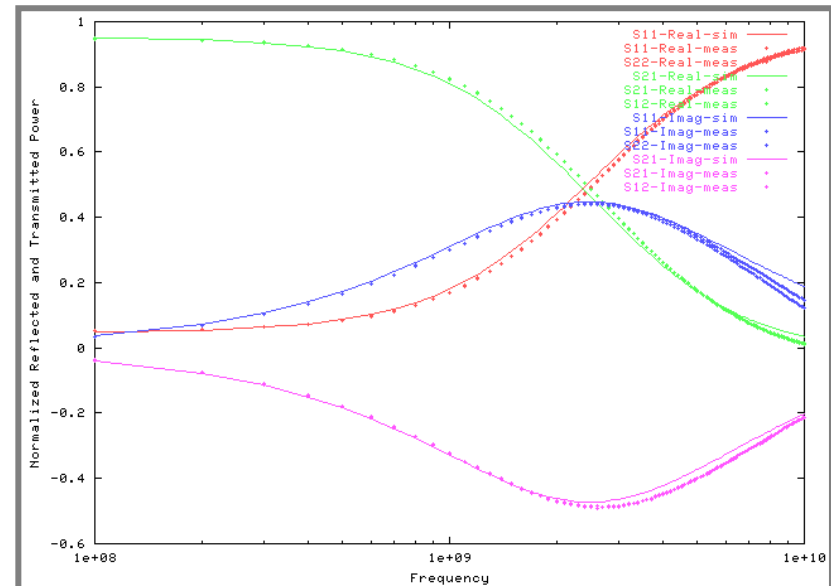
## Validate Using Test Chips



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**Measured vs Simulated  $\sim 1$  nH**



**Measured vs Simulated  $\sim 7$  nH**



# A Real Design

**Start with what Designer knows:**

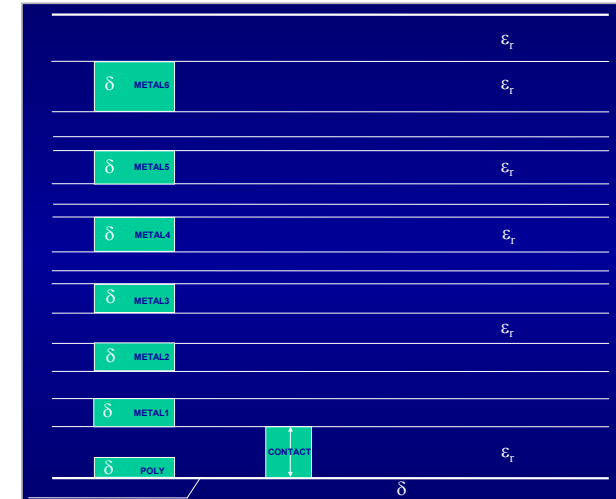
- **Physical Process Description**
- **Frequency Range or desired frequency**
- **Desired Inductance**
- **Minimum Acceptable Quality Factor**



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## Process Technology File

```
// spiral technology file:
//*****
technology CMOS
units microns
metal
layer 0 -300.0 -1.0e+00 0.1 //gnd
layer 5 -1.0 0 10 //epi
layer 8 1.2 1.7 3.3e-6 //met1
layer 9 1.7 2.3 6.0e-05 //via1
layer 10 2.3 2.8 3.3e-6 //met2
layer 11 2.8 3.4 6.0e-05 //via2
layer 12 3.4 3.9 3.3e-6 //met3
layer 18 3.9 4.5 6.0e-05 //via3
layer 19 4.5 5.0 3.3e-6 //met4
layer 20 5.0 5.6 6.0e-05 //via4
layer 21 5.6 6.5 3.3e-6 //met5
layer 22 6.5 7.1 6.0e-05 //via5
layer 23 7.1 9.2 3.3e-6 //met6
endmetal
dielectric
layer 1 0.000 10.0 3.9 //oxide
layer 2 10.000 11.0 6.0 //nitride
enddielectric
endtechnology
```





## A Real Inductor Design

### Example Design Specification:

- Frequency Range -- Example 2 GHz through 3 GHz
- Desired Inductance -- 3 nH
- Need Quality Factor  $> 8$  @ 2.4 GHz
- Impedance at 2.4GHz =  $2 \cdot \pi \cdot F \cdot L = 45$  Ohms





## An Aside: Three Definitions of Q

- Simplest Definition: (Zero at Resonance)

$$\frac{-\text{Imag}(Y_{11})}{\text{Real}(Y_{11})}$$

- 3-dB Bandwidth Definition:

$$\frac{\omega_o}{2} \left. \frac{d\phi}{d\omega} \right|_{\omega_o}$$

- Most General Definition

$$\left. \frac{\text{Energy Stored}}{\text{Energy Dissipated}} \right|_{\text{one cycle}}$$



## A Real Design: Starting Questions

- What topology to use?
  - Helix, spiral, symmetric, number of sides
- Which metal(s) to use for winding and bridge?
  - Single metal, double metal, series or parallel metals
- What length, width and inner radius to use?

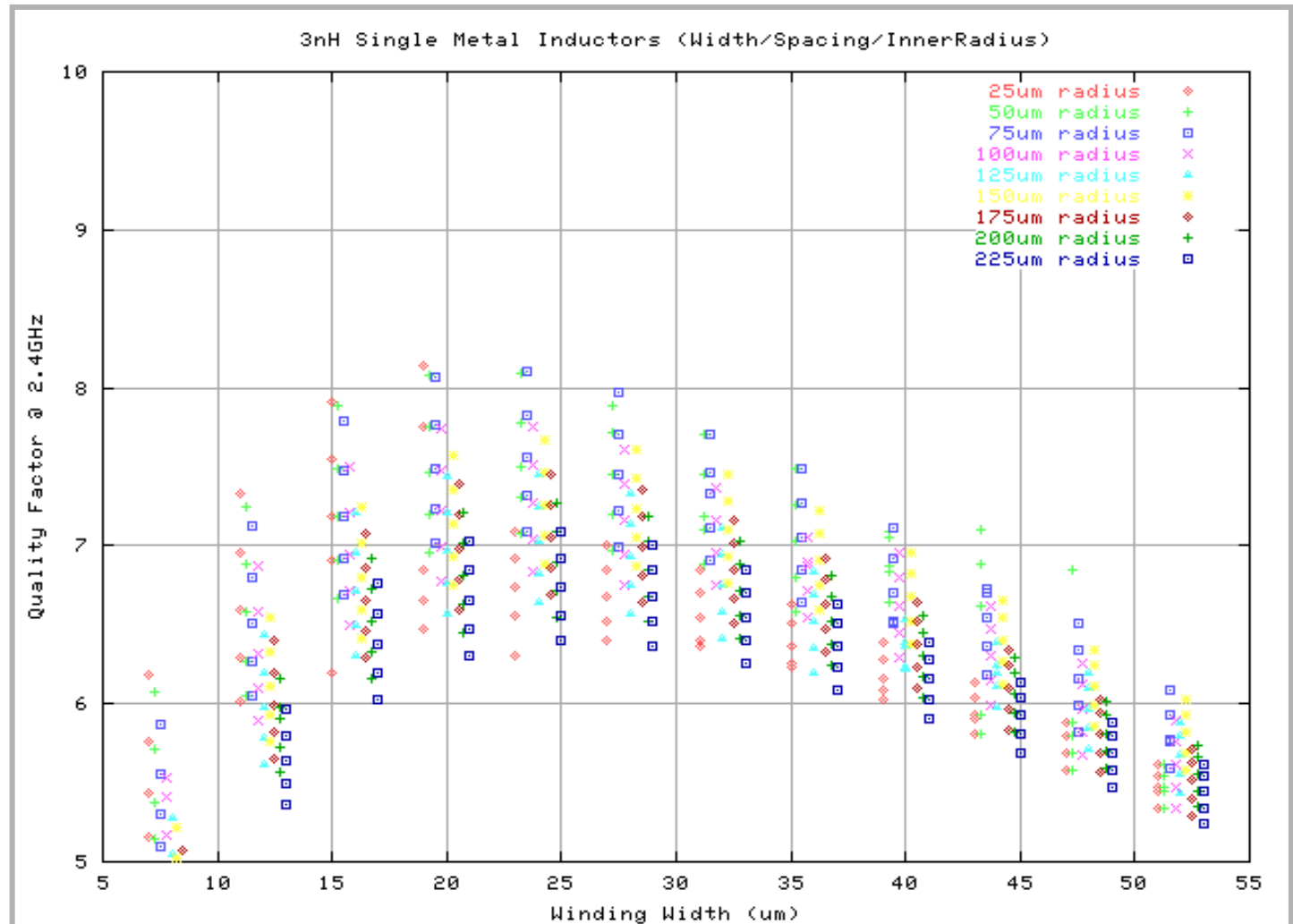


## SPIRAL Control File

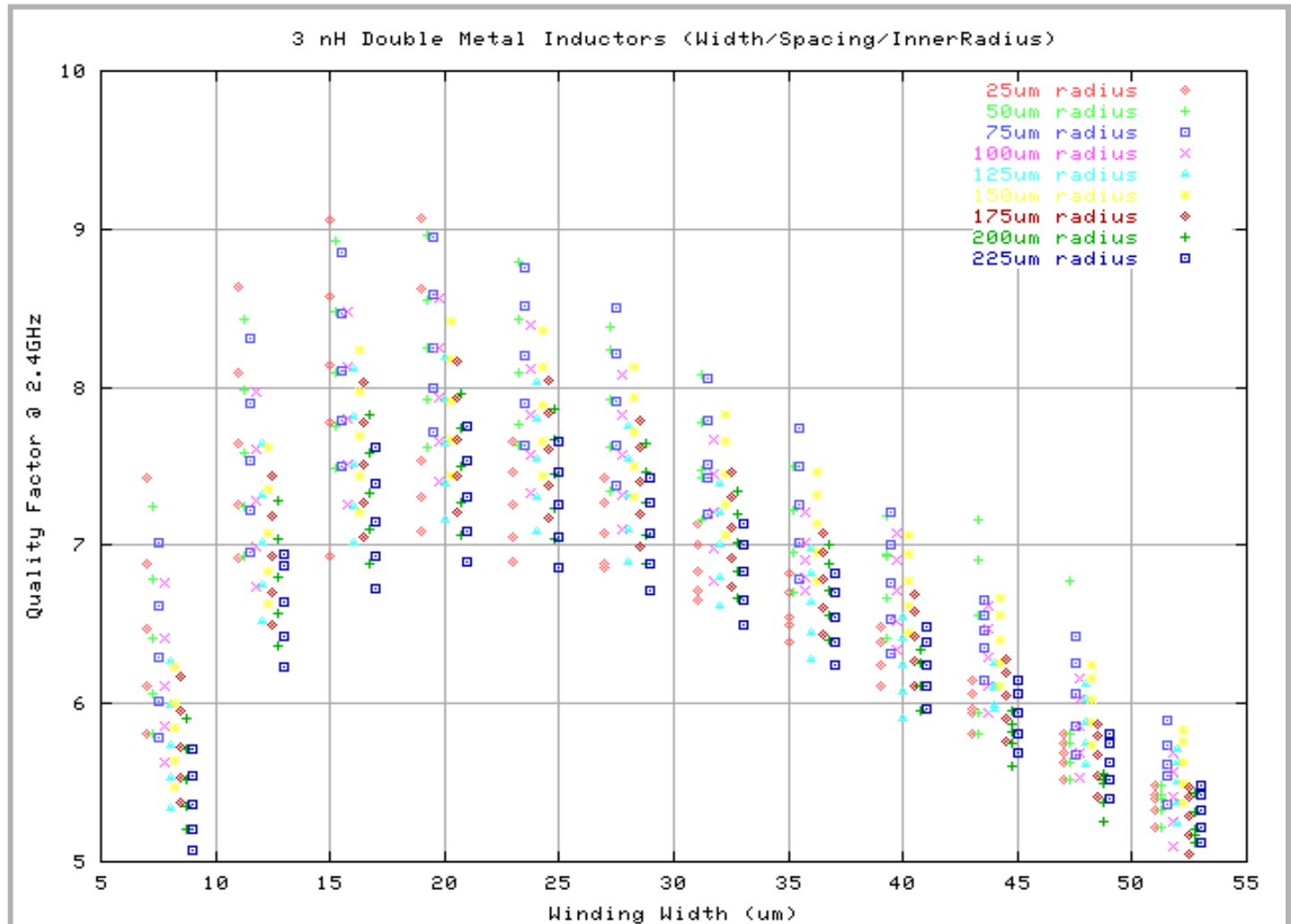
```
CELL L3nH
TARGET ind
*GROUND_LAYER 0 5
GROUND_LAYER 0
PLANAR
UNITS MICRON
SOLVE
GROUND_TYPE TARGET_ONLY
*FLOAT
SKIN
1PORT
FREQUENCY LIN 2 2.4e+9
          2.5e+9
SNAP_TO_GRID 0.05
```

```
SPIRAL ind
ESCAPE STRAIGHT
TYPE DOUBLE METAL
SIDE_NUMBER 8
CHOICE L
DESIRED_INDUCTANCE 3.0e-09
WIDTH              :-<) 8 52 4 (>-:
SPACING            :-<) 2 10 2 (>-:
INNER_RADIUS       :-<) 25 225 25 (>-:
BRIDGE_GAP 3
SPIRAL_LAYER 23
VIA_LAYER 22
BRIDGE_LAYER 21
ORIGIN 0.0 0.0
*vIA_SIZE 2
*vIA_SPACING 2
*vIA_ENCLOSURE 1
ENDSPIRAL
```

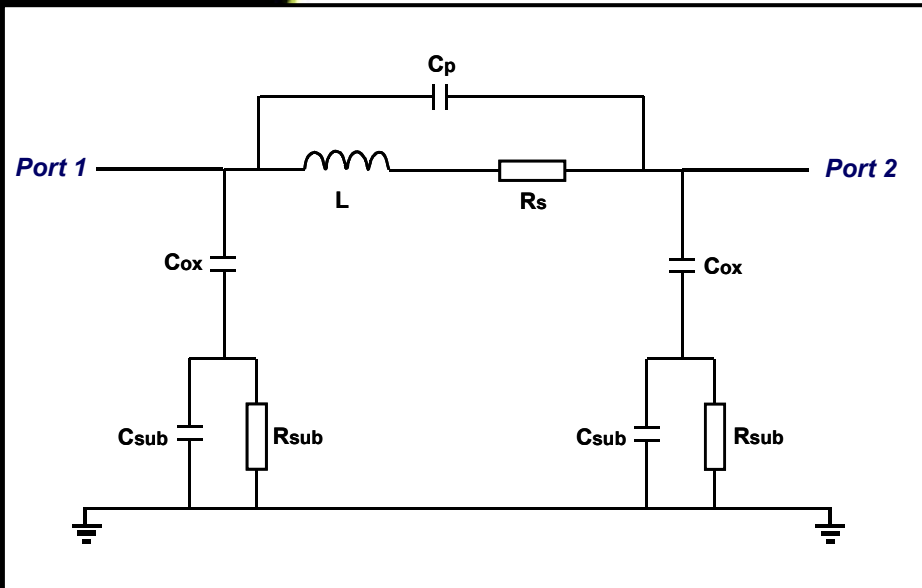
## SPIRAL Output 3nH Single Metal - Octagon



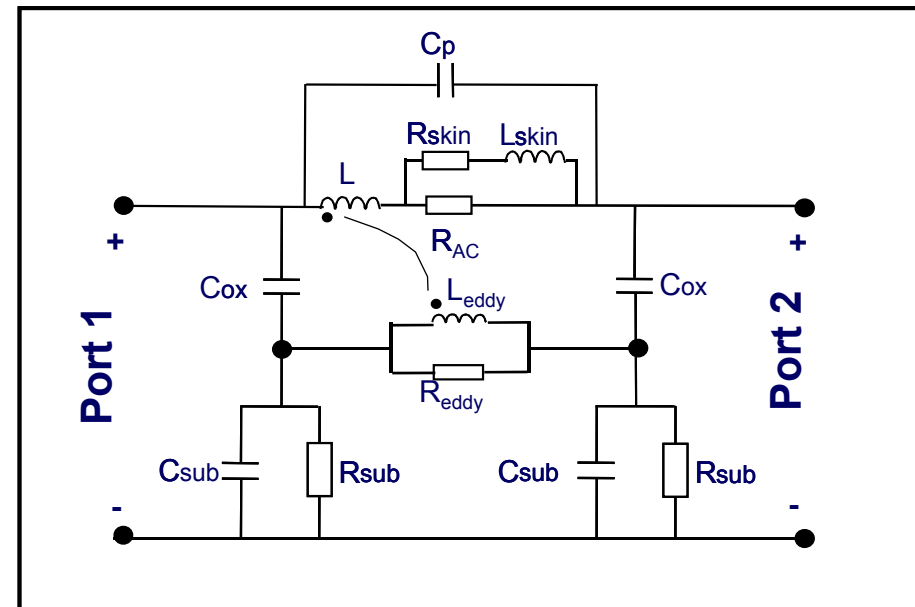
## SPIRAL Output 3nH Double Metal - Octagon



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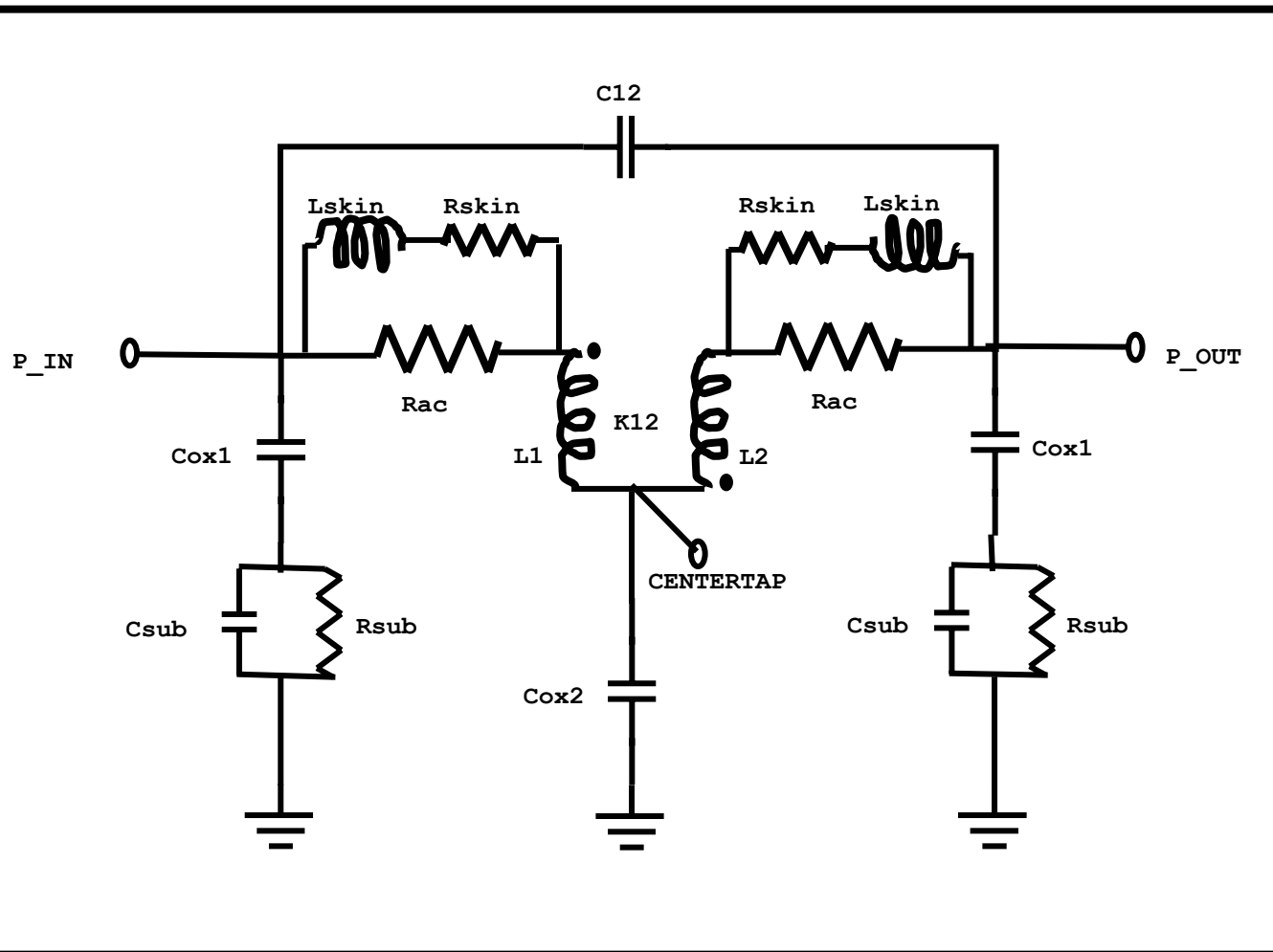


## Model Fitting: Simple 9 Element Model



## Enhanced 13 Element Model Plus 1 Inductive Coupling

## Symmetric Inductor Lumped Model





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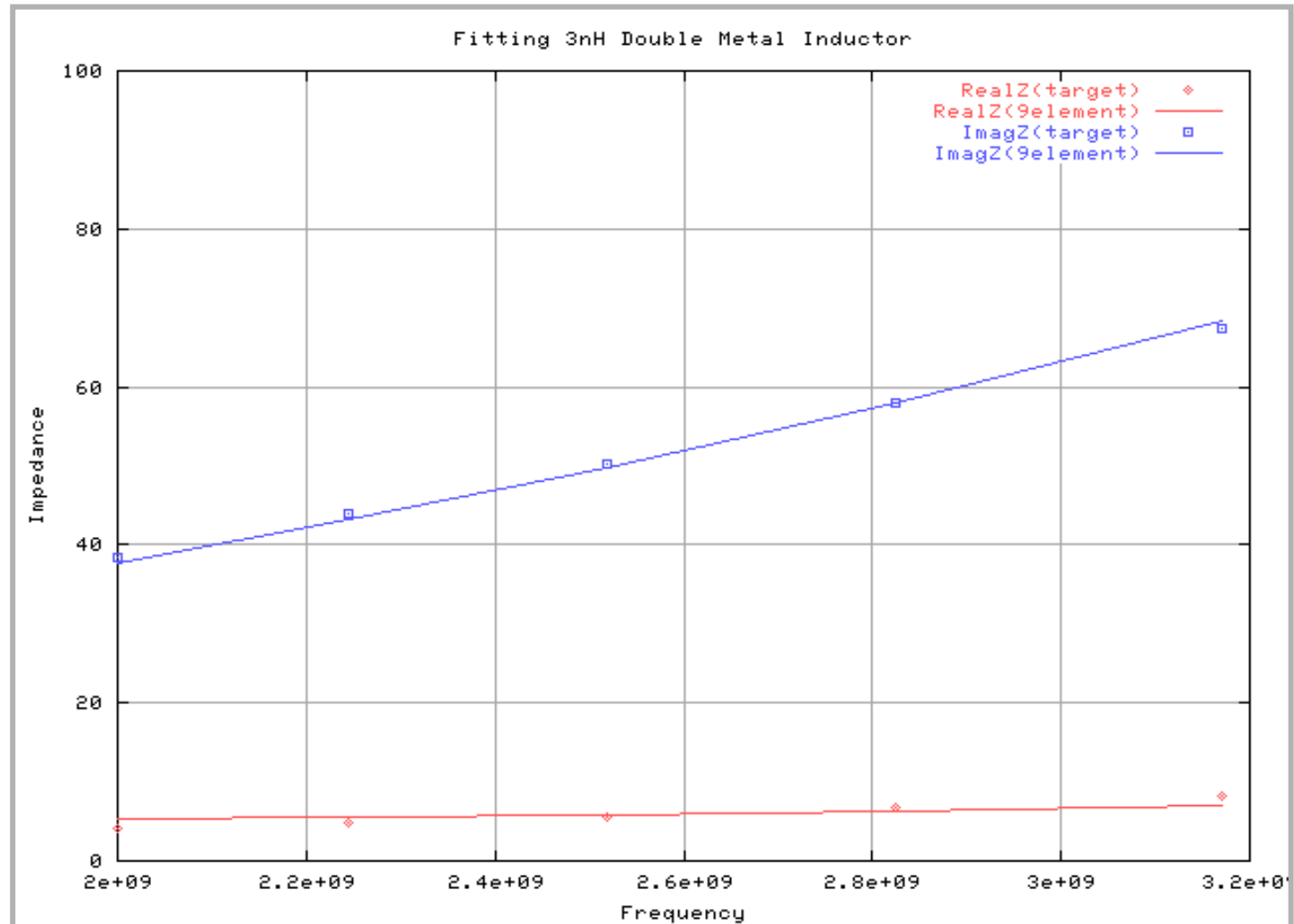
## SPIRAL Control File: Fitting

```
CELL L3nH
TARGET ind
*GROUND_LAYER 0 5
GROUND_LAYER 0
PLANAR
UNITS MICRON
SOLVE
GROUND_TYPE TARGET_ONLY
*FLOAT
SKIN
1PORT
FREQUENCY DEC 20 1e+8 10e+9
*FREQUENCY DEC 20 2e+9 3e+9
SNAP_TO_GRID 0.05
FIT_MODEL9
*FIT_MODEL13
*FIT_SYMMETRIC
```

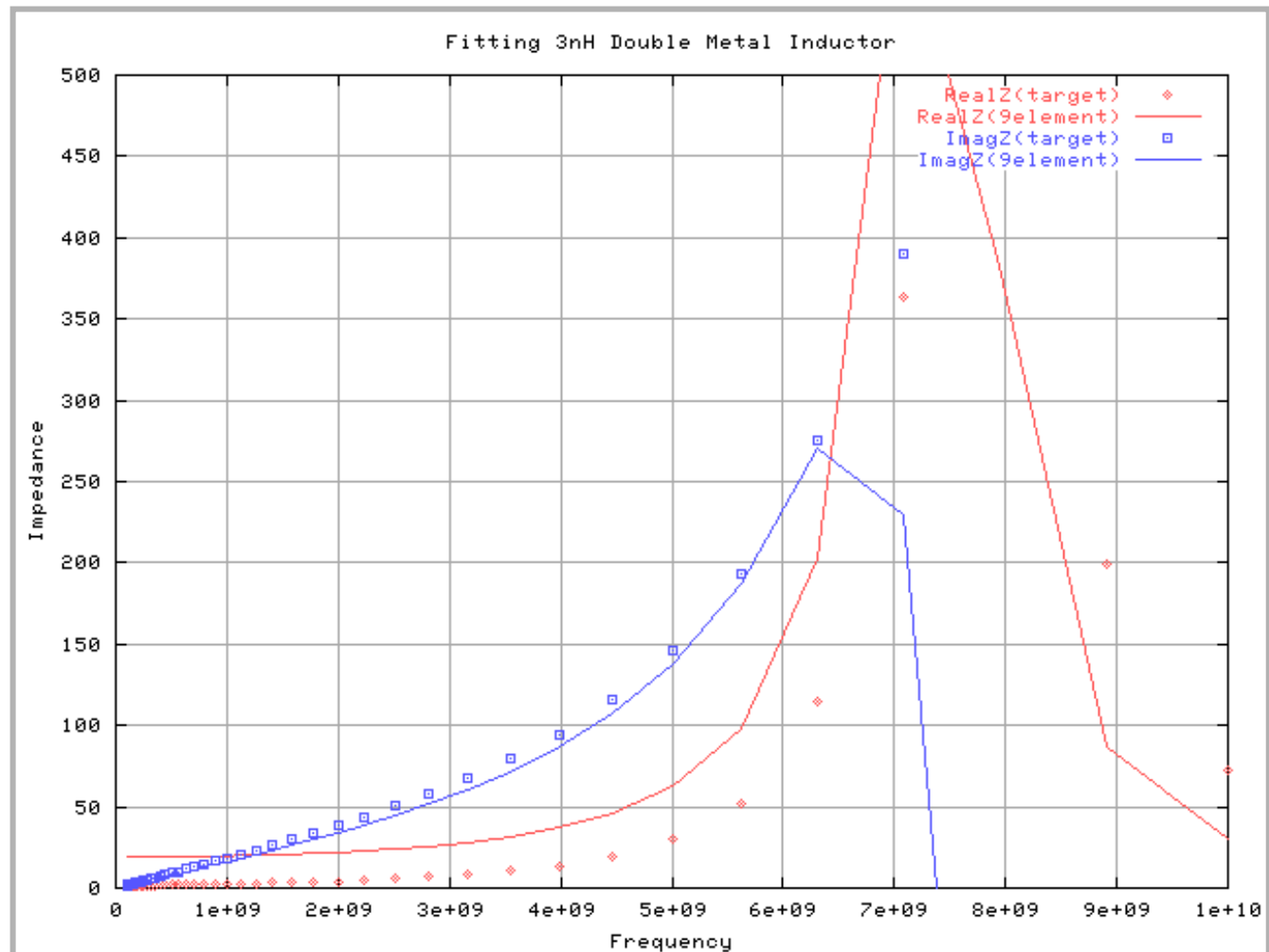
```
SPIRAL ind
ESCAPE STRAIGHT
TYPE DOUBLE_METAL
SIDE_NUMBER 8
CHOICE L
DESIRED_INDUCTANCE 3.0e-09
WIDTH 20
SPACING 2
INNER_RADIUS 25
BRIDGE_GAP 3
SPIRAL_LAYER 23
VIA_LAYER 22
BRIDGE_LAYER 21
ORIGIN 0.0 0.0
VIA_SIZE 2
VIA_SPACING 2
VIA_ENCLOSURE 1
ENDSPIRAL
```



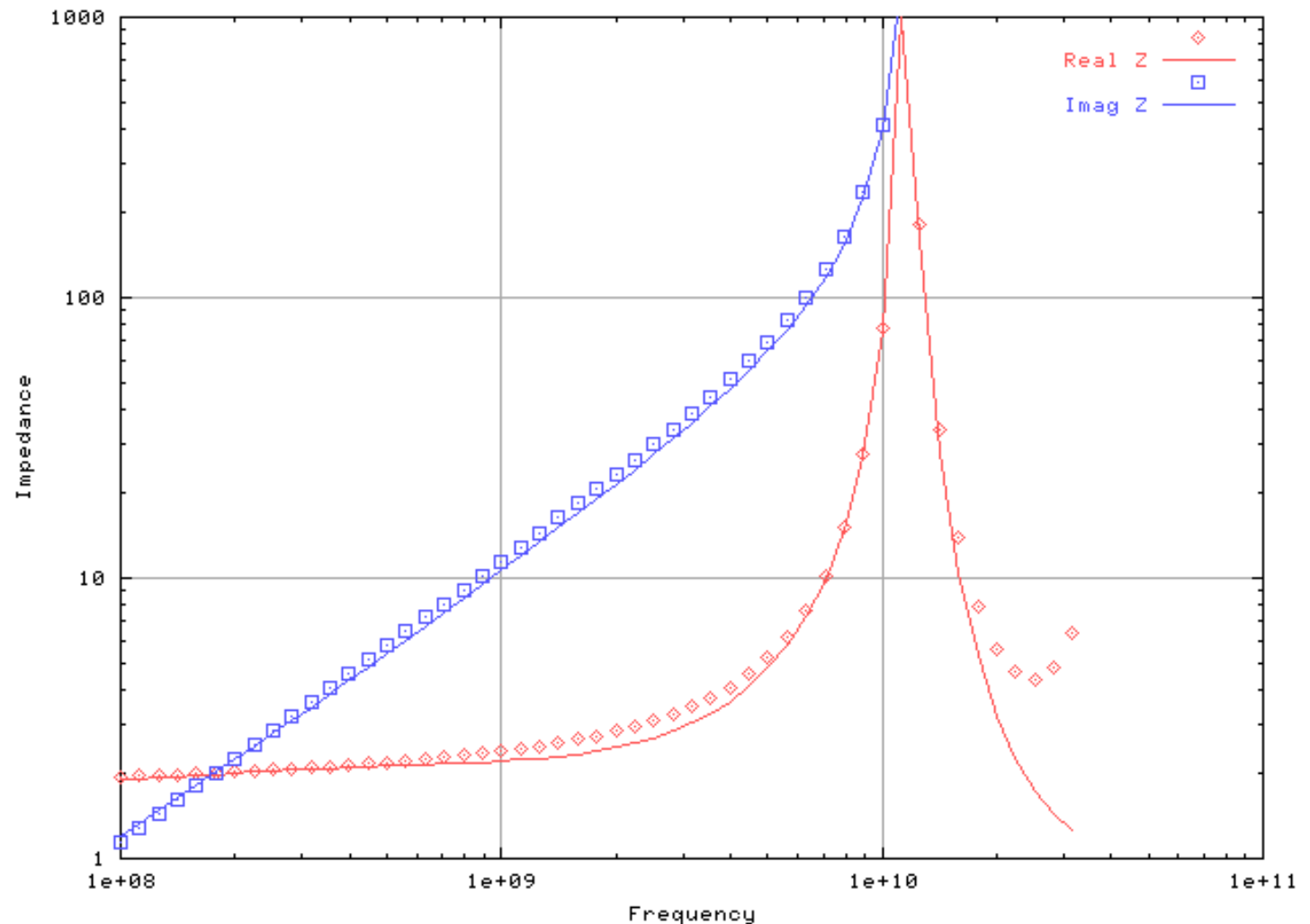
## Narrow Band 9 Element Model Fit



## Broadband 9 Element Model Fit



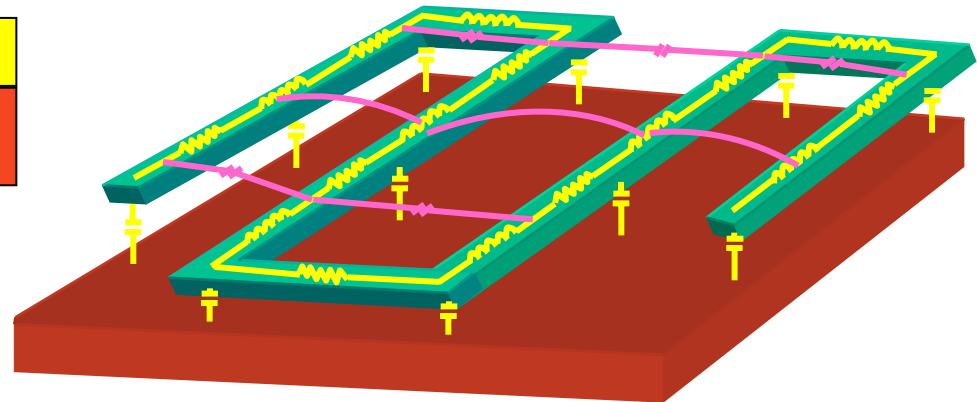
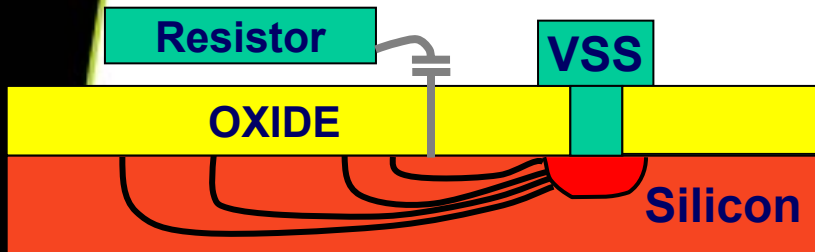
## Broadband 13 Element Model Fit



## Resistive Components

### Thin Film Resistors (Not as Simple as they Look)

- Large Devices with Distributed Resistance and Capacitance
- Could Include Significant Substrate Effects
- Asymmetry Could Cause Noise Pickup from Substrate



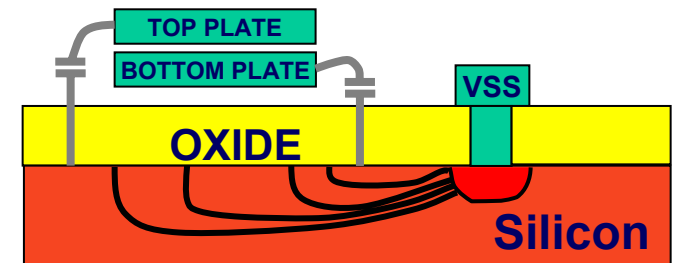
- What is the coupling across segments?
- What is the coupling through the substrate?



## Capacitive Components

### ▪ MIM Capacitors

- Large distributed structures
- Asymmetric with respect to substrate

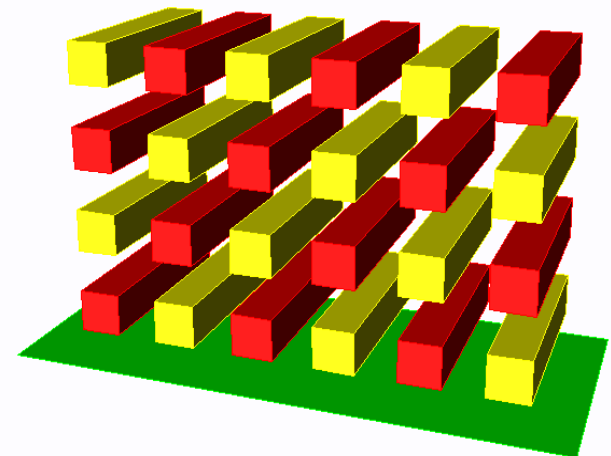


### ▪ Multi-layer Interdigitated Capacitors

- OEA Patented technique
- Optimize Q, Capacitance Density, Parasitic Capacitance, etc...
- Symmetric relative to substrate (minimize noise pickup from substrate)
- Include skin and proximity effects

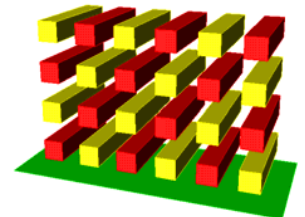
### ▪ Control of undesired effects

- Minimize non-linear behavior
- Eliminate high resistance well contact
- Optimize selection and usage of metals
- Optimize finger width and spacing
- Optimize placement of metal straps



## Multi-layer Interdigitated Capacitors

Finger W/S( $\mu$ )	Finger L ( $\mu$ )	Capacitance (fF)	Density (fF/ $\mu^2$ )	Parasitic Cap (%)
0.080	5.2	300	9.70	1%
0.100	6.5	321	6.64	1%
0.120	7.8	326	4.69	1%
0.150	9.8	340	3.13	2%
0.200	13.0	362	1.87	3%
0.250	16.3	383	1.27	4%
0.300	19.5	411	0.95	5%
0.400	26.0	473	0.61	8%
0.800	52.0	857	0.28	14%





# FABLESS SEMICONDUCTOR ASSOCIATION

## OEA RF/Analog Software Products

### ***SPIRAL™***

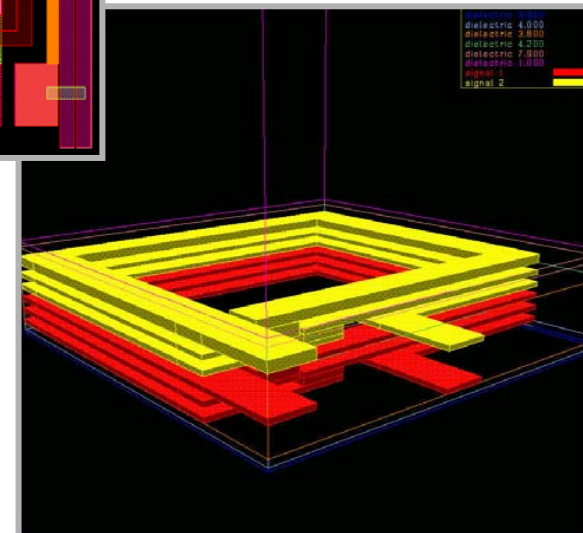
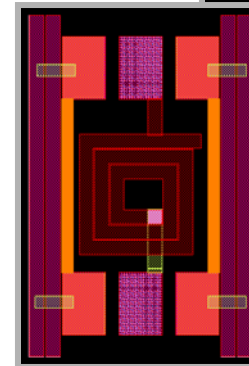
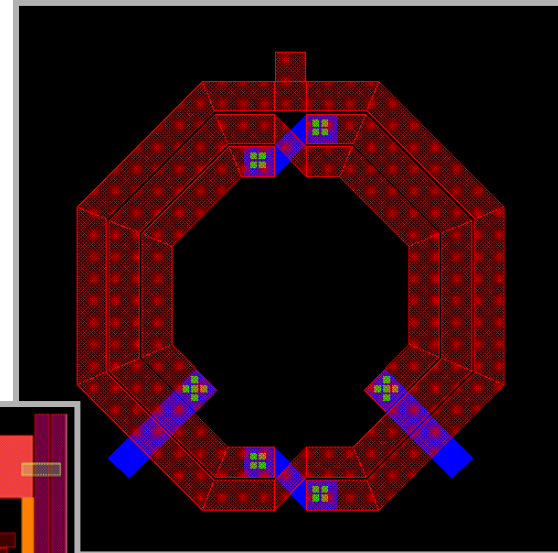
- Includes all relevant effects (skin, substrate, etc...)
- Synthesizes a large variety of inductors
- Can examine thousands of designs in a few hours
- Generates layout, Spice, Z & S parameters
- Can fit to many simplified models
- Optimization engine included

### ***RF-PASS™***

- Outputs N-Port Y, Z and S parameters
- Handles much more complex substrates and designs
- Optimization of arbitrarily complex passive structures

### ***SUBSTRATE NOISE ANALYSIS***

- Calculates full-chip substrate noise couplings
- Enables what-if exploration of isolation strategies
- Allows design planning before layout



## Conclusions

- **Spiral Inductor Design is Not Simple as It Looks**
- **Selecting a Spiral from a Pre-characterized Library Does Not Do the Job!**
- **It is Possible to Design a Spiral or Group of Spiral Inductors Easily with the Right Software**
- **High Q and Very High Capacitance Design Structures can be Designed to Save Valuable Chip Real-estate by Using the Proper Tools**

